

Measurement of Nanometer Electron Beam Sizes with Laser Interference using IPBSM

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Jacqueline Yan, M.Oroku, Y. Yamaguchi, S. Komamiya
(The University of Tokyo, Graduate School of Science)

T. Yamanaka, Y. Kamiya, T. Suehara,
(The University of Tokyo, ICEPP)

T. Okugi, T. Terunuma, T. Tauchi, S. Araki, J. Urakawa (KEK)

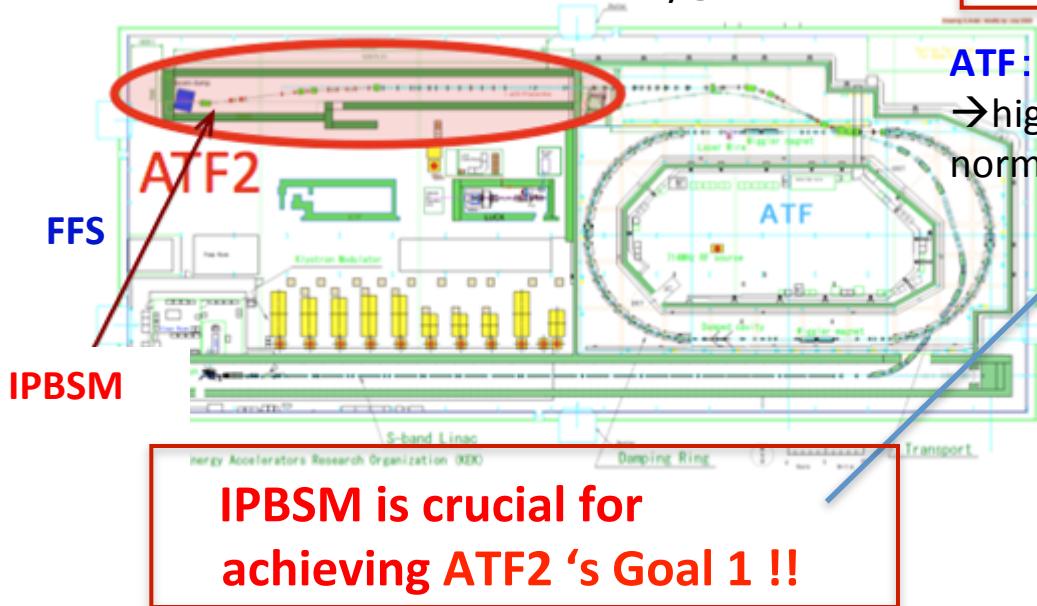


Role of IPBSM (Shintake Monitor) at ATF2

ATF2: Linear Collider FFS test facility@KEK

$$L = \frac{n_b N^2 f_{rep}}{4\pi\sigma_x\sigma_y} H_D$$

For high luminosity
must focus
vertical beam size at IP !!
flat beam : $\sigma_y \ll \sigma_x$



ATF: 1.28 GeV LINAC , DR
→high quality e- beam with extremely small normalized vertical emittance $\gamma\varepsilon_y$

ATF2 Goal 1 :
focus σ_y^* to design size 37 nm
→verify Local Chromaticity Correction

ATF2 Goal 2:
O(nm) beam trajectory stabilization

OUTLINE

measurement scheme, performance, beam tuning roles

Beam Time results
2011~2012

upgrades

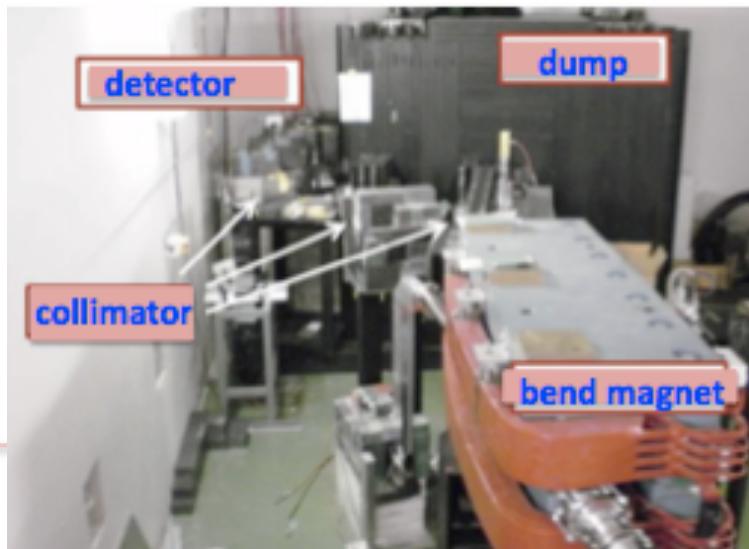
Summary & Goals

Measurement Scheme

use laser interference fringes as target for e- beam

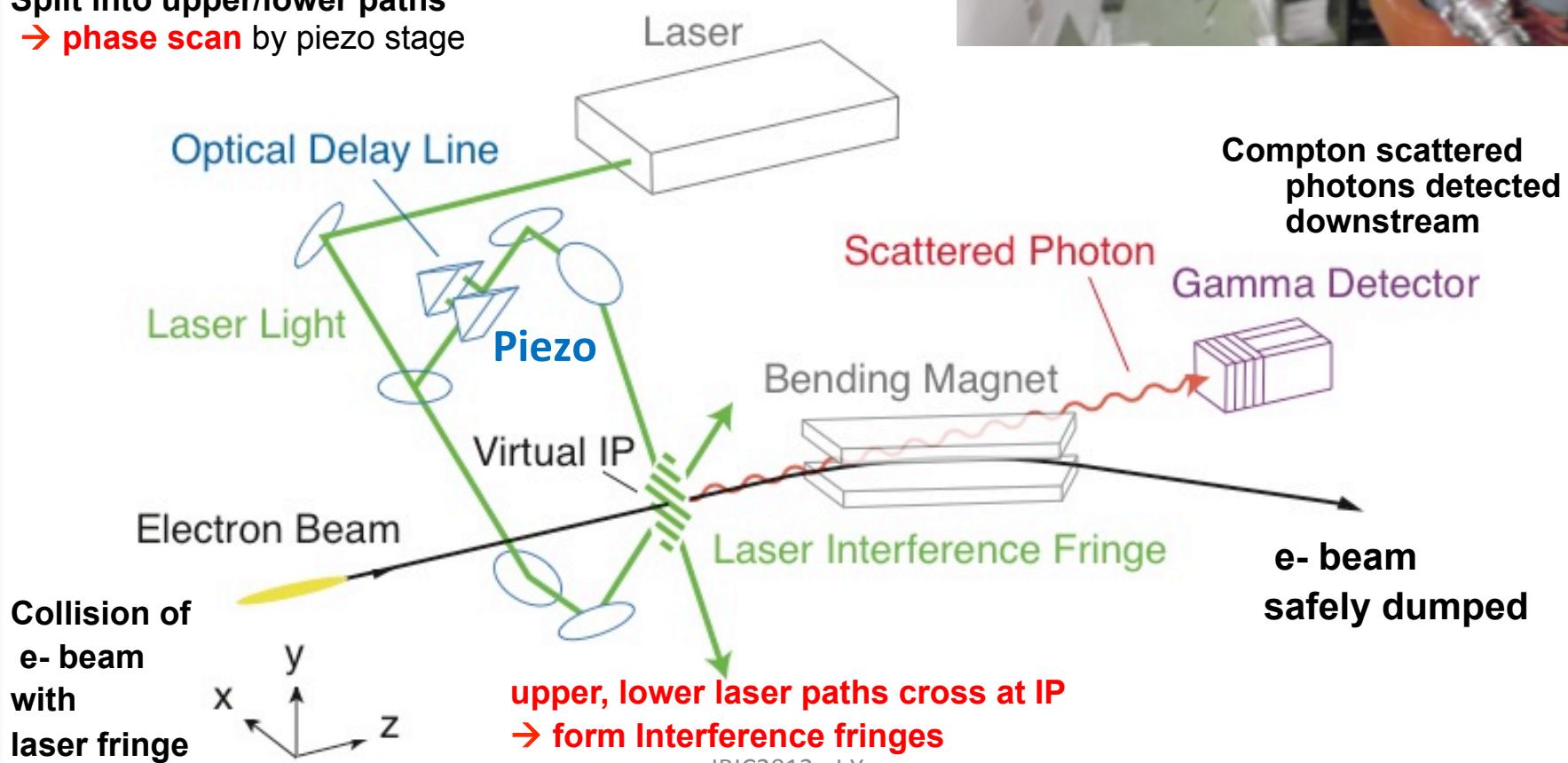
Only device able to measure $\sigma_y < 100 \text{ nm} !!$

- Crucial for beam tuning
→ realization of future linear colliders



Split into upper/lower paths

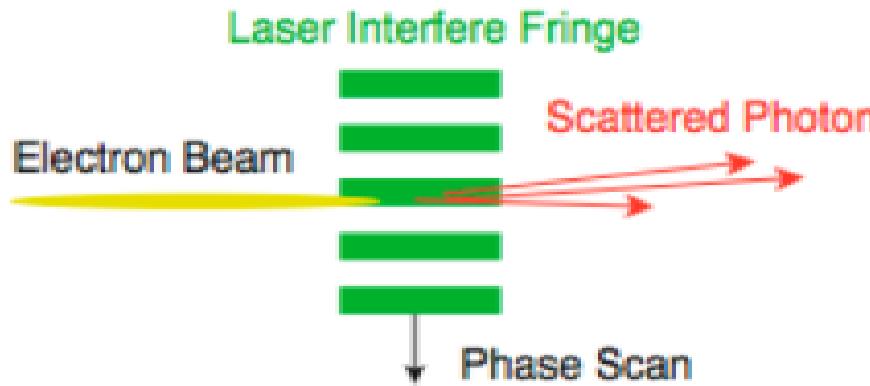
→ phase scan by piezo stage



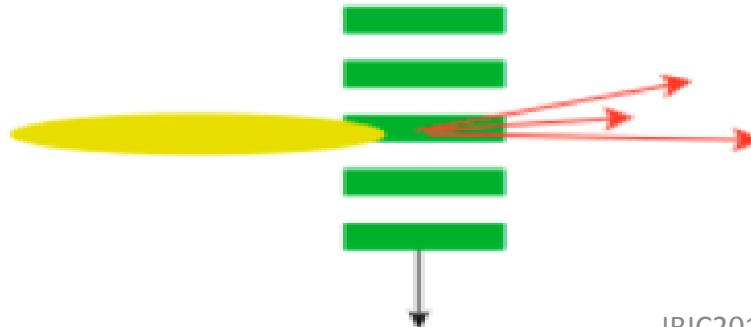
Detector measures
signal **Modulation Depth "M"**

$$M = \frac{N_+ - N_-}{N_+ + N_-} = |\cos(\theta) \exp(-2(k_y \sigma_y)^2)|$$

$$\Rightarrow \sigma_y = \frac{d}{2\pi} \sqrt{2 \ln \left(\frac{|\cos(\theta)|}{M} \right)}$$



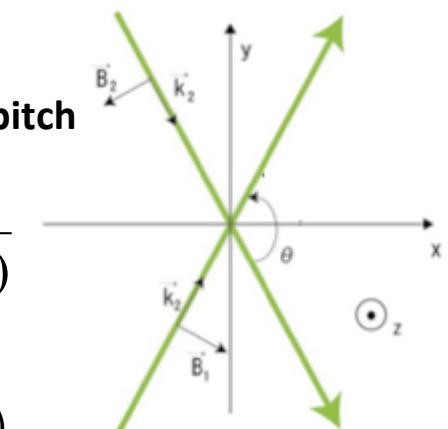
N: no. of Compton photons
Convolution between e- beam profile and fringe intensity



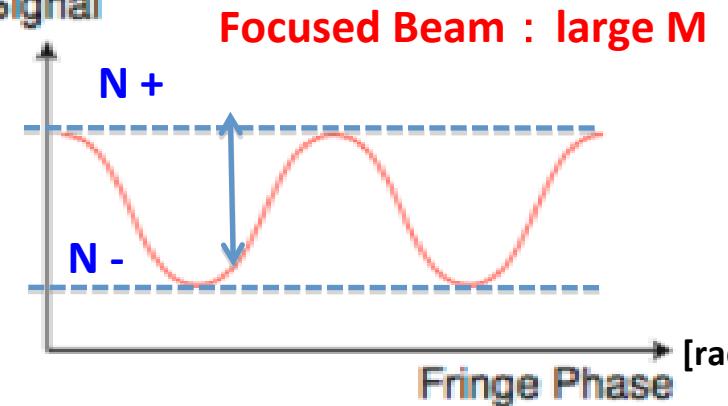
measurable range
determined by **fringe pitch**

$$d = \frac{\pi}{k_y} = \frac{\lambda}{2 \sin(\theta/2)}$$

depend on
crossing angle θ (and λ)

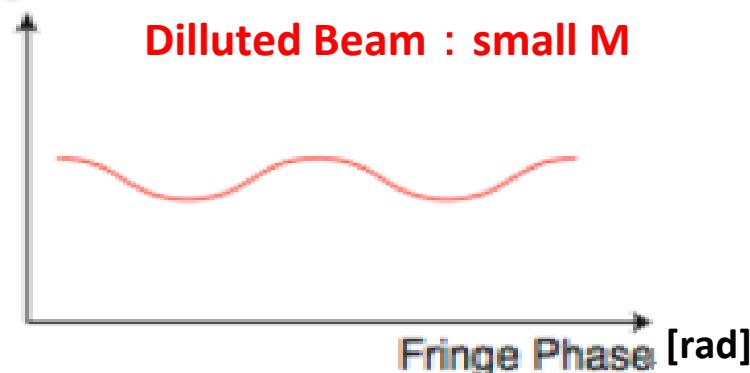


Signal



Signal

Dilluted Beam : small M



Crossing angle θ	174°	30°	8°	2°
Fringe pitch	266 nm	1.03 μm	3.81 μm	15.2 μm
$d = \frac{\pi}{k_y} = \frac{\lambda}{2 \sin(\theta/2)}$				
Lower limit	20 nm	80 nm	350 nm	1.2 μm
Upper limit	110 nm	400 nm	1.4 μm	6 μm

Expected Performance

$37 \pm 2 \text{ (stat.) } {}^{-0}_{+4} \text{ (syst.) nm}$

Measures

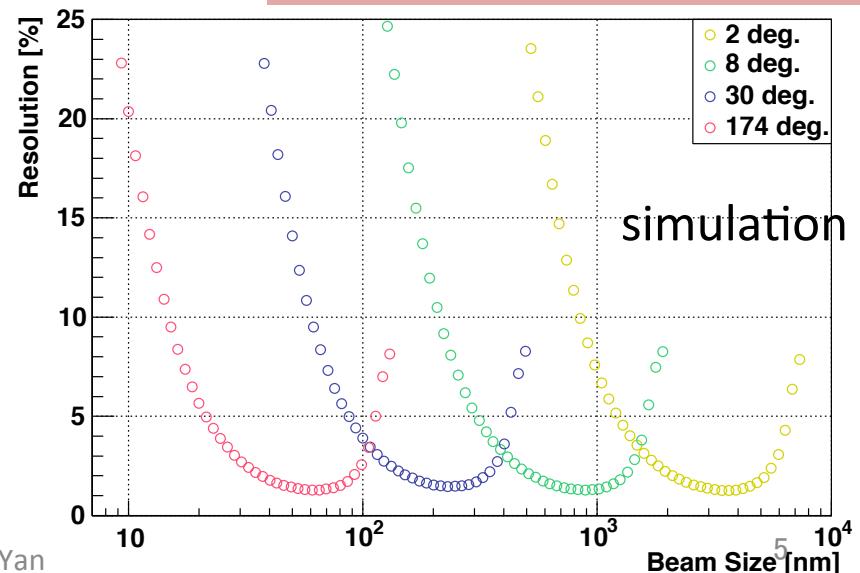
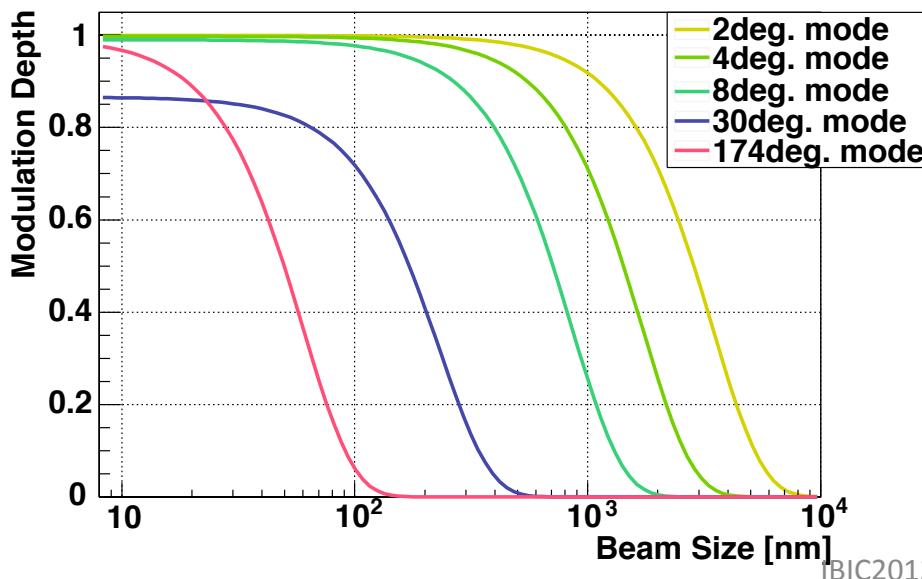
$\sigma_y^* = 20 \text{ nm } \sim \text{few } \mu\text{m}$
with < 10% resolution

$$\sigma_y = \frac{d}{2\pi} \sqrt{2 \ln \left(\frac{|\cos(\theta)|}{M} \right)}$$

σ_y^* and M for each θ mode

must select appropriate mode
according to beam focusing

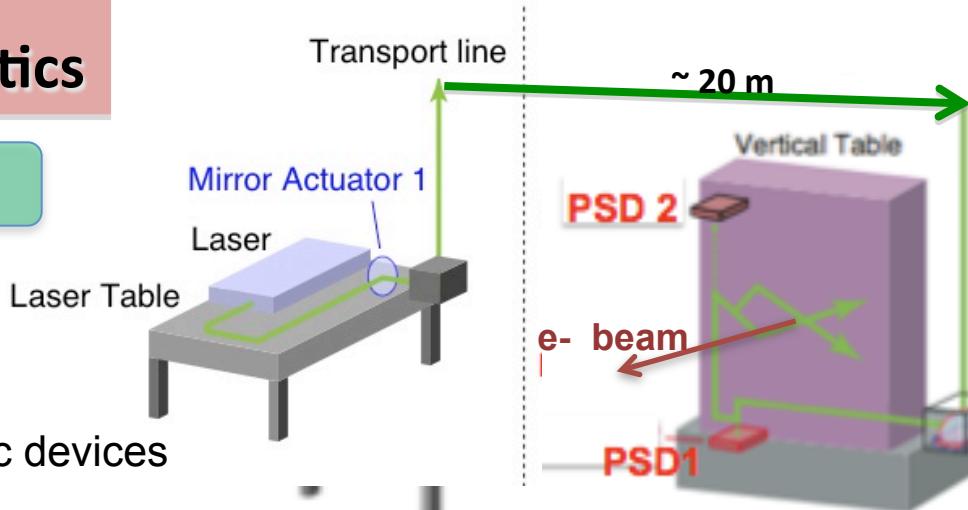
Resolution for each θ mode



Laser Optics

Laser table

- Source (SHG)
- diagnostic devices



Vertical table

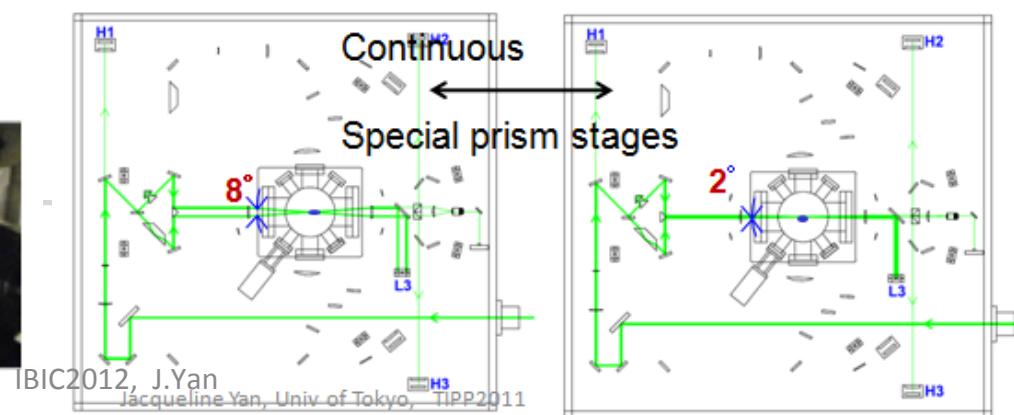
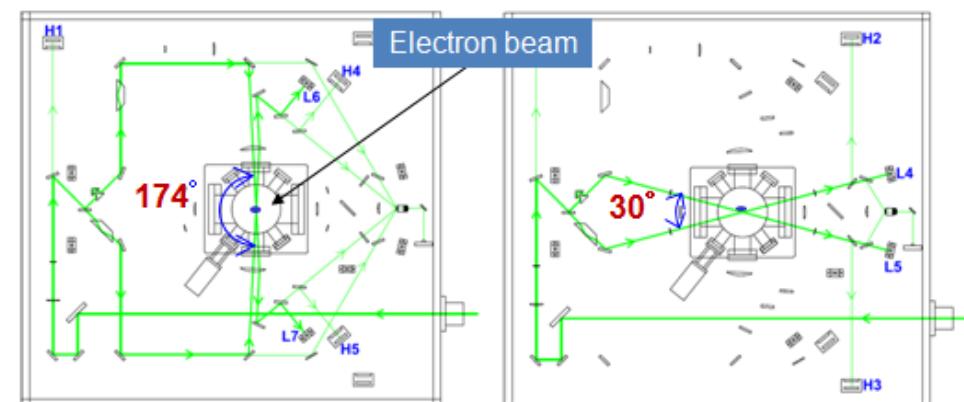
Interferometer

- Phase control → piezo stage
- construct path for each θ mode (auto-stage + mirror actuators)

Nd :YAG
Q-Switch laser

PRO350
Spectra Physics

Wavelength	532 nm (SHG)
Pulse Energy	1.4 J
Peak power	164 MW
Pulse Width	8 ns (FWHM)
f_{rep}	6.25 Hz
Line Width	< 0.003 cm ⁻¹
Timing Stability	< 0.5 ns
Energy Stability	± 3%



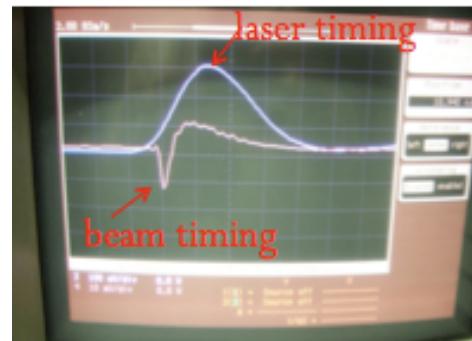
Role of IPBSM in Beam Tuning

1 path construction: access to IP, confirm precision with “ eyes & hands”

switch e- beam ON → remote control

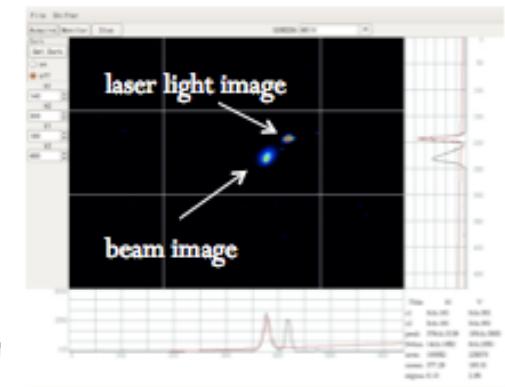
2 Timing alignment

Timing scan of laser Q-SW and e- beam
→ matched with precise TD2



3 Preliminary position alignment

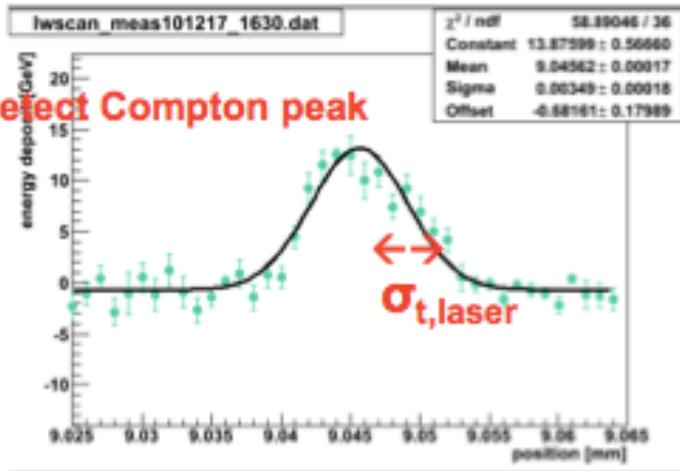
Overlap laser and e- beam spots on screen monitor
(within $\sim 20 \mu\text{m}$)



extremely precise position alignment

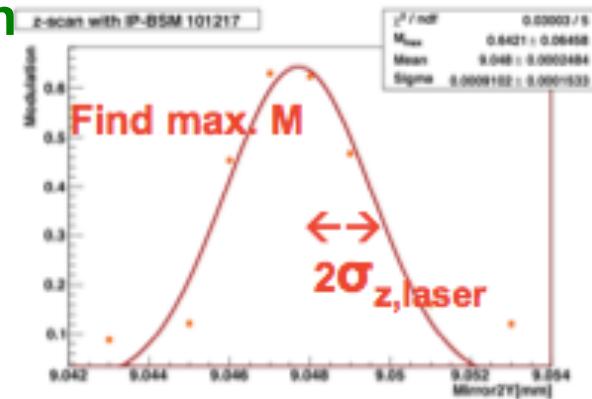
4 transverse : detect Compton peak

laser wire scan



5 Longitudinal :

z scan



6 After all preparations

continuously measure σ_y^* using interference mode
→ Feed back to beam tuning

post-earthquake recovery and upgrade in 2011

- overall stabilization of laser optics
- suppress signal jitters

Beam Time (autumn~)

σ_y^* focused down to $\sim 1 \mu\text{m}$
(beam tuning issues)

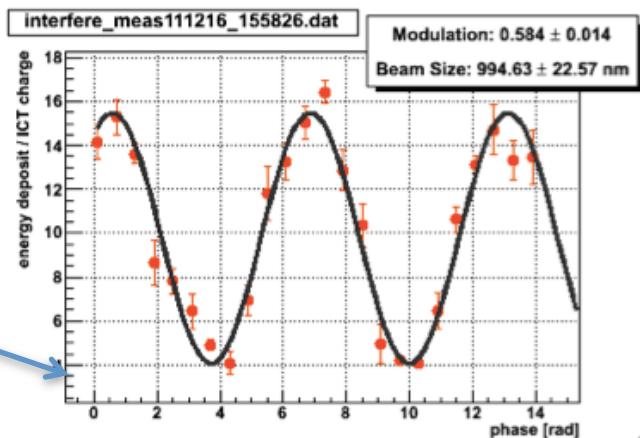
IPBSM resolution improved
(2 – 8 deg mode)



Large jitters
 $\sim 30\%$

Hardware
upgrade

*much smaller jitters
clear contrast*



overcome signal jitter sources (example)

Beam size jitter

high response , effective
status monitors
& scan software
introduced to ATF2

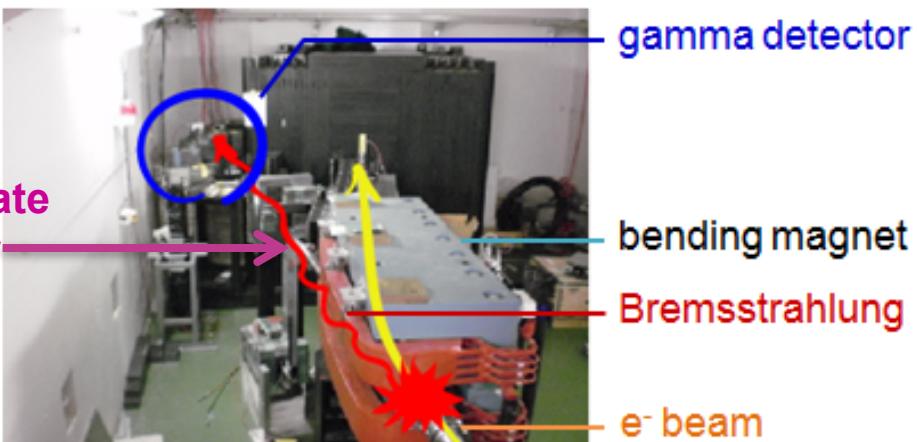
→ monitor instability factors
on beam/laser profile

fast M detection → scan under stable conditions

extra bremsstrahlung at post-IP dipole

High BG

intermediate
collimator
installed



Beam time status in 2012

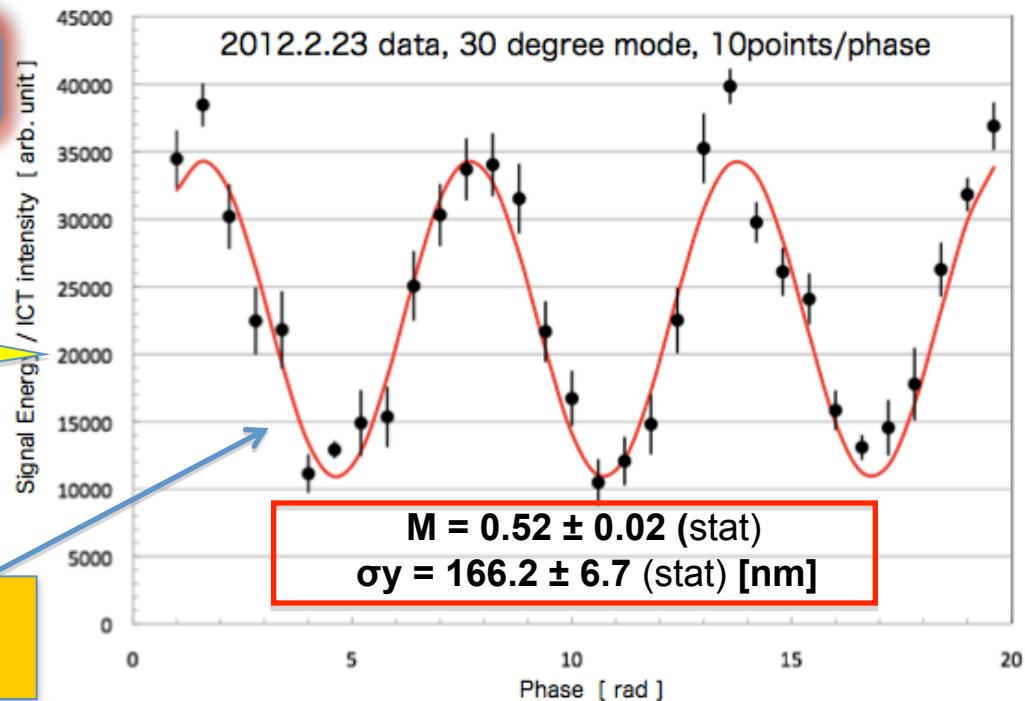
full commissioning
of 30° mode

First Modulation detection

(10 x β_x^* , 10 x β_y^* optics)

stably measure $\sigma_y^* \sim 160 \text{ nm}$

(10 x β_x^* , 3 x β_y^* optics)



2 - 8 ° mode

Measured larger σ_y (\sim few 100 nm)
with clear contrast
(i.e. high M : 0.8 – 0.9)

- ➔ Syst error study
- ✓ upper limit on M_meas
- ✓ consistency of σ_y _meas

Began commissioning of 174 ° mode

- hardware check
- Optimization of scan strategies

Obstacles (2012 Feb)

- Beam condition drift (over many hours)
- Not very focused σ_y^* (still at 3 x β_y^* optics)

one more step before full commissioning of
174 ° mode i.e. consistent fringe scans

Systematic Error Study

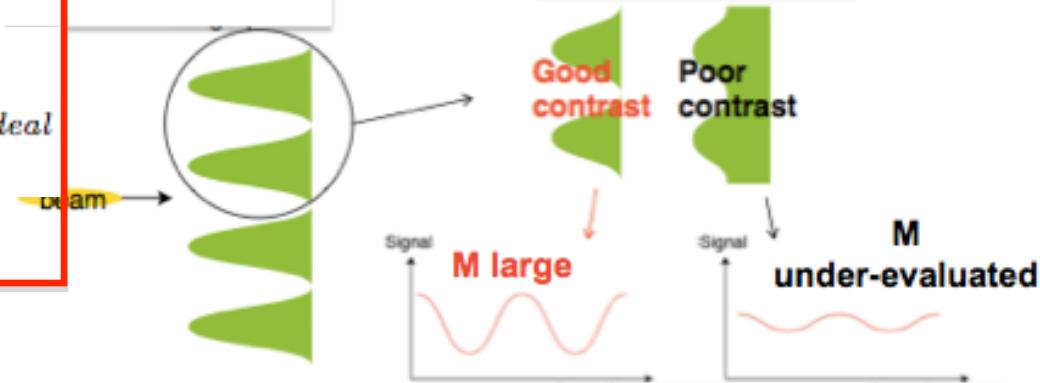
Interpretation of
M under-evaluation / σy^* over-evaluation)

Modulation Reduction Factor

$$M_{meas} = C_1 C_2 \dots M_{ideal} = \left(\prod_i C_i \right) M_{ideal}$$

$$\sigma_{y,ideal}^2 + \frac{1}{2k_y^2} \left| \sum \ln C_i \right|$$

degraded fringe contrast due to bias



Example of syst error evaluation
(June, 2012 ,4 deg mode)

major
bias
factors

Laser profile imbalance

compare Compton signal
of upper / lower path laser wire scans

Fringe tilt

limited by alignment precision

Phase jitter (relative position)

$C_{phase} > 95\%$

Laser path alignment

Ct,pos : ~ 100%, Cz,pos : > 99.5%

M reduction
“worst limit”

polarization

> 98% adjusted to nearly pure S state

From actual data:

upper limit on M (= “fringe contrast”)

Ctotal = 0.8 – 0.9

Improve through 2012 summer upgrade

Profile Imbalance

- ✓ peak power
- ✓ IP spot size σ_{laser}

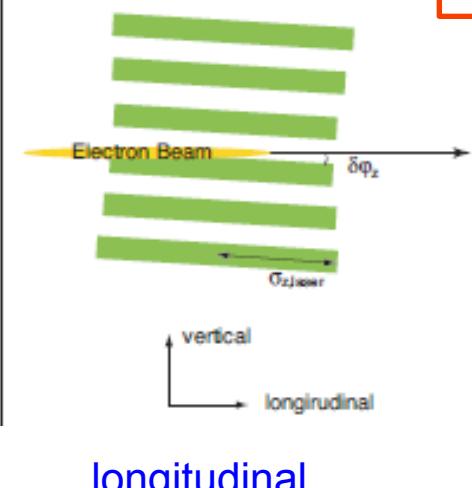
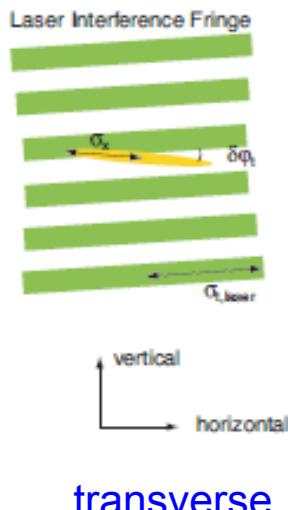
◆ partially: optical components related loss
 (transmission, reflection, delay line)
 total $P_t = 0.88$)

2 times difference in
 laser-wire
 Compton signals ($N_{\text{av}} = 20$)

$$M' = CM = \frac{2\sqrt{P_t}}{1+P_t} M$$

◆ lens misalignment
 → Difference in focal point position

$$P_t \equiv P_U / P_D$$

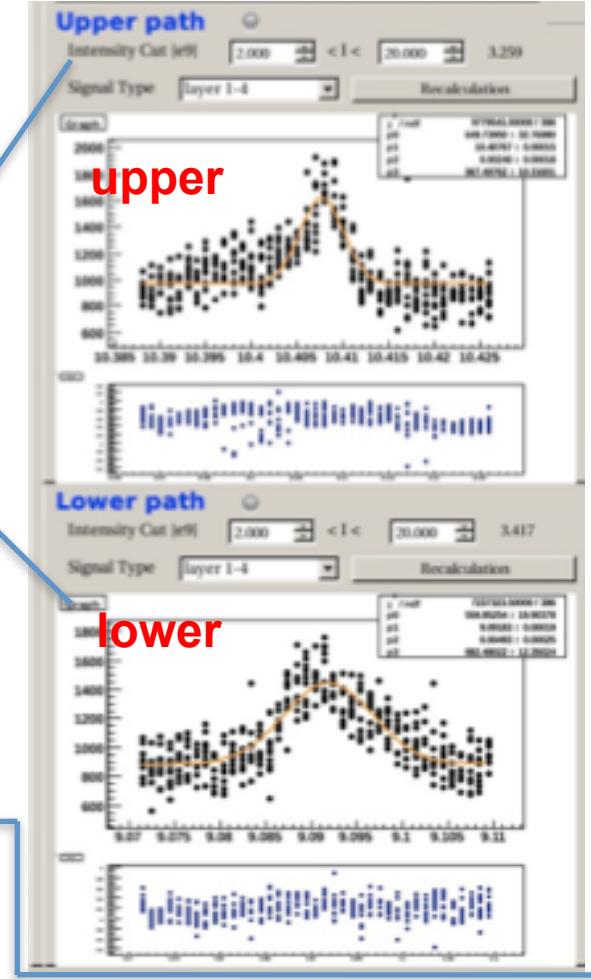


Fringe Tilt

fringe not formed
 perpendicular
 to e- beam axis

→ improve alignment precision
 on final focus lens before IP

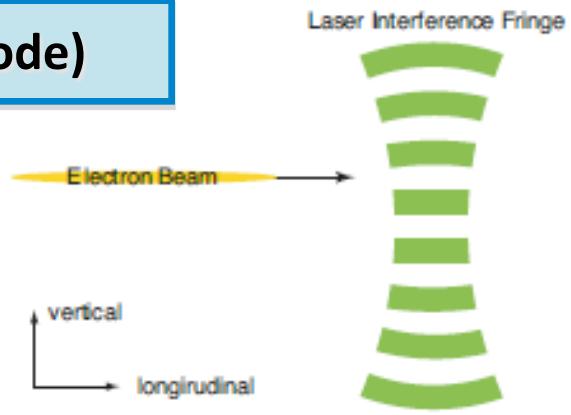
observable limit: $\Delta = 3 - 5$ mm
 ↔ tilt $\delta\phi_{t,z}$: 5 - 20 mrad



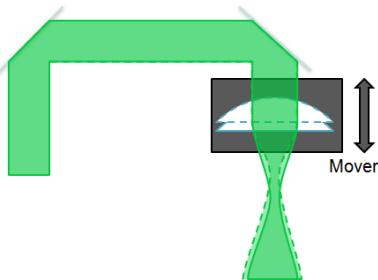
Syst. Errors specific to very small σ_y^* (174 deg mode)

Spherical wavefronts

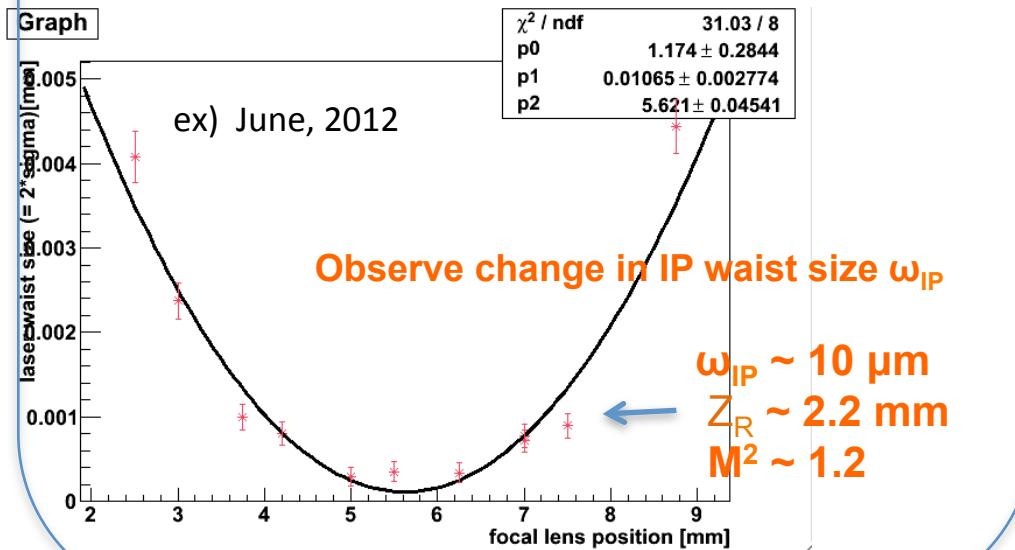
Offset of ultra-focused e- beam vs laser waist → distorted fringes
 $C_{\text{sphere}} > 99.7 \%$



Solution is **focal point scan**

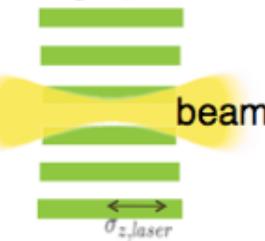


attach mover to lens
→ align focal point to IP
within < 100 μm
($\sim 0.1^*\text{Rayleigh length } Z_R$)



Change of σ_y^* within fringes

fringe pattern

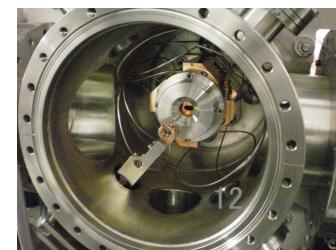


due to strong focusing,
 $C_{\text{growth}} \sim 99.7\%$

Tiny σ_y^* is very sensitive to relative position jitter !!!

IPBPM (O(nm) design resolution)
under commissioning

- beam pos. monitoring
- feedback correction



Stabilization of laser system



transport line
→ insulation,
anti-vibration

Insulated mirror box

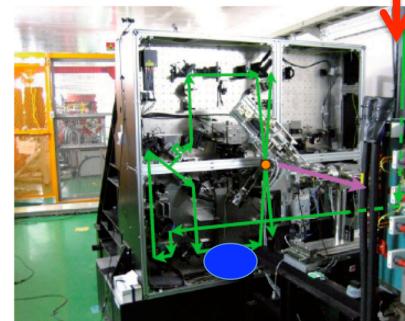
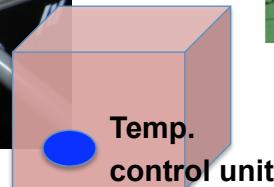
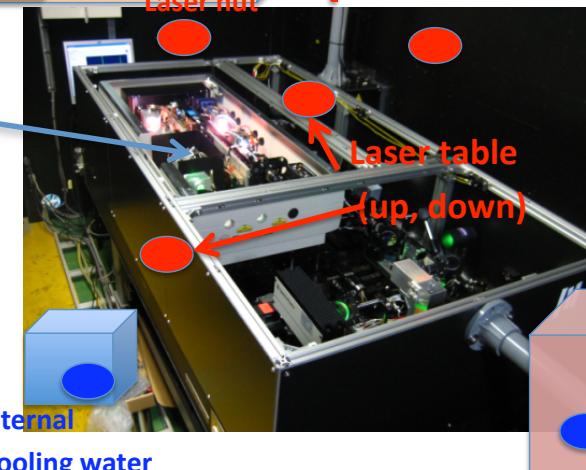
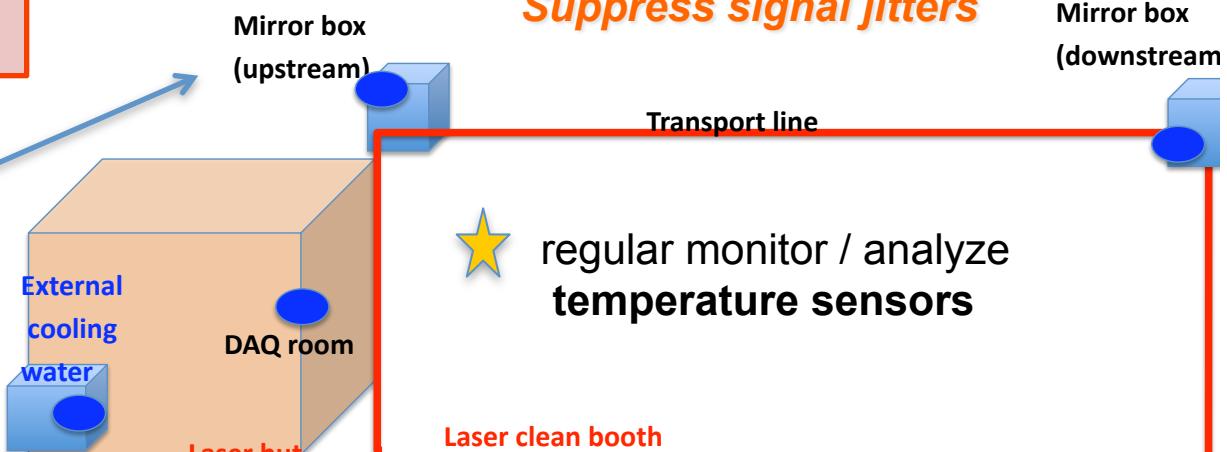
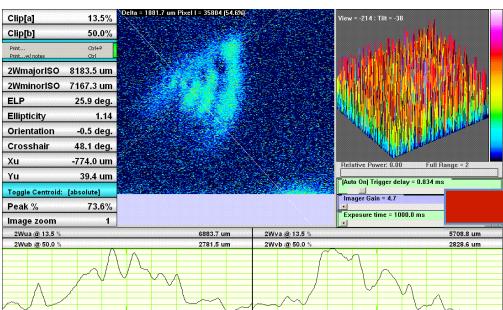
long term path stabilization

Beamlok (piezo feedback)
added to laser cavity

Improved pointing stability
 $< \pm 50 \mu\text{rad} \rightarrow < \pm 25 \mu\text{rad}$

improve oscillation, profile

Tuning / exchange of
cavity mirrors, seeder, flash-lamp



cleaner environment...

protective booth
@ IP vertical table

Maintain dust-free
component surfaces



2012 summer: **major upgrade of laser optics**

Goal: **alignment precision & reproducibility**

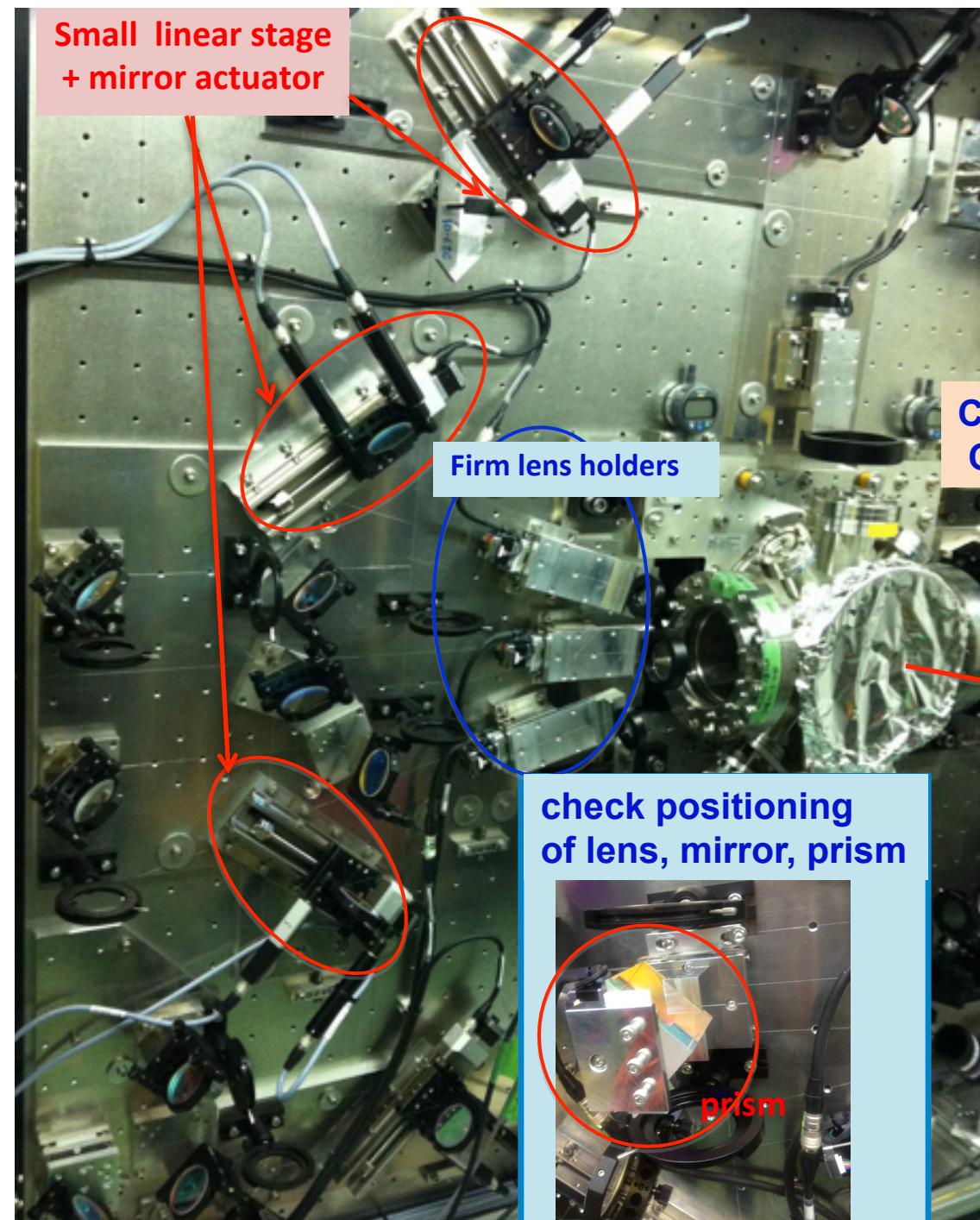
- suppress syst. errors
- effective small σ_y^* tuning
- better conditions to accomplish goals in autumn beam run

BEAM TIME GOAL:

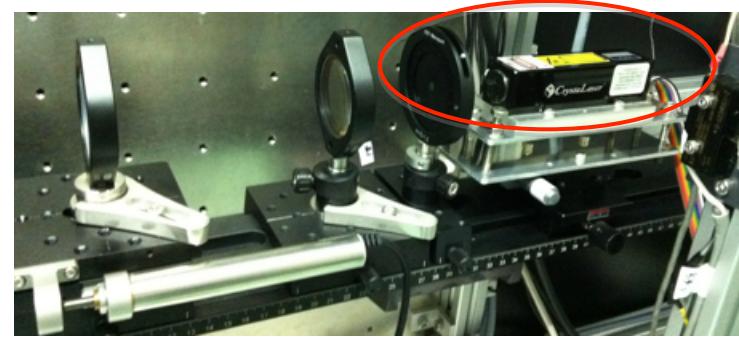
- ◆ Full commissioning of 174° mode
 - stably measure $\sigma_y^* < 100$ nm
 - focus down to $\sigma_y^* \sim 37$ nm

improvements	details
easier alignment match focal point to IP Injection position / angle into lens	<ul style="list-style-type: none">• focal point scan for all modes• redefine clear reference lines on new base plates
consistency , reproducibility esp. before / after mode switching	<ul style="list-style-type: none">• new θ switching method {small linear stage + mirror actuators } independent for each mode (instead of shared rotating stages)• re-commission PSD system → monitor jitters / drifts
profile imbalance focal point difference between upper/lower paths	<ul style="list-style-type: none">• suppress path length difference in new design

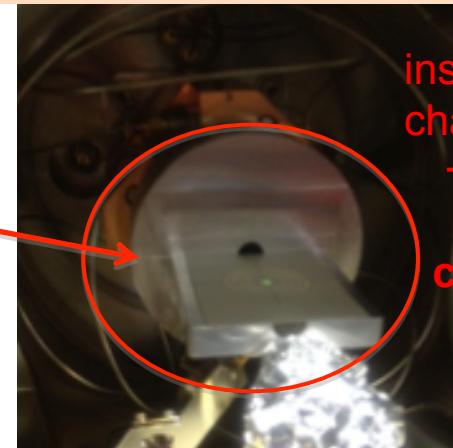
Small linear stage
+ mirror actuator



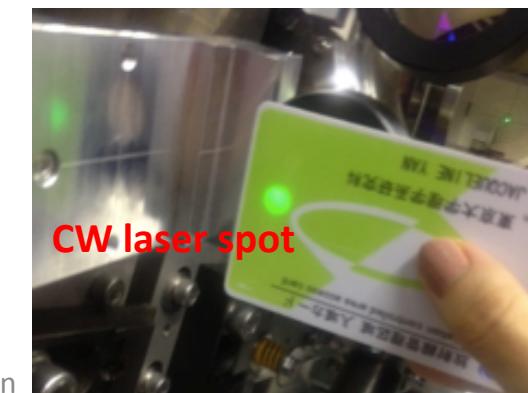
just after injection onto vertical table



Confirm fine alignment using
CW laser and transparent IP target



inside IP
chamber
→laser waist
&
crossing point



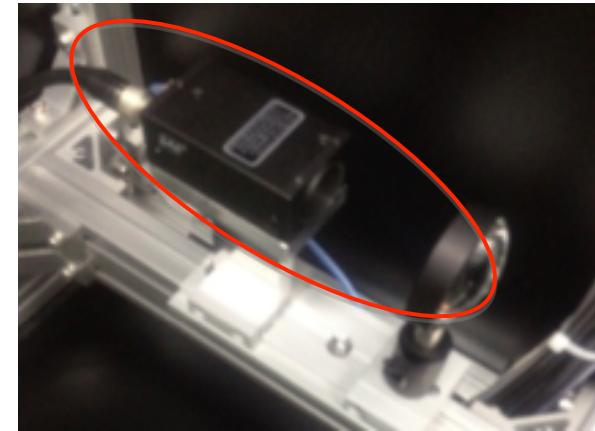
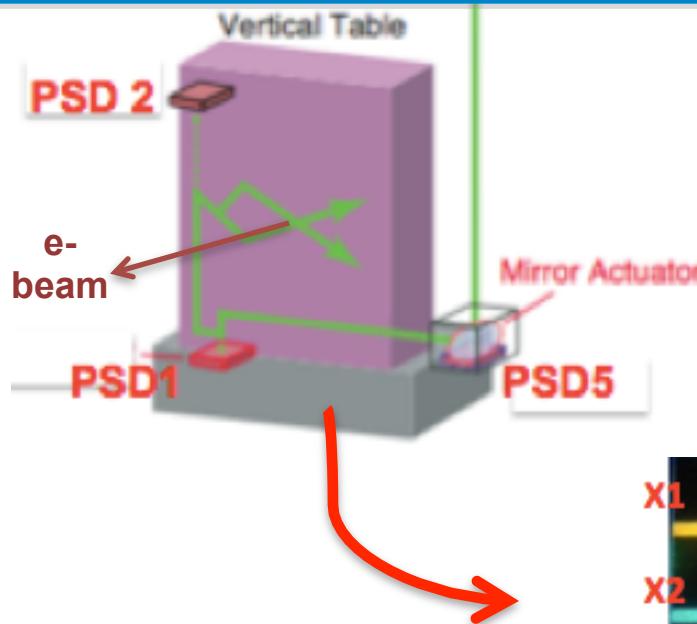
Schedule:

assembling of new setup completed

❖ Now (Sep, 2012) : Beam off tests prepare for autumn run (10/15~)

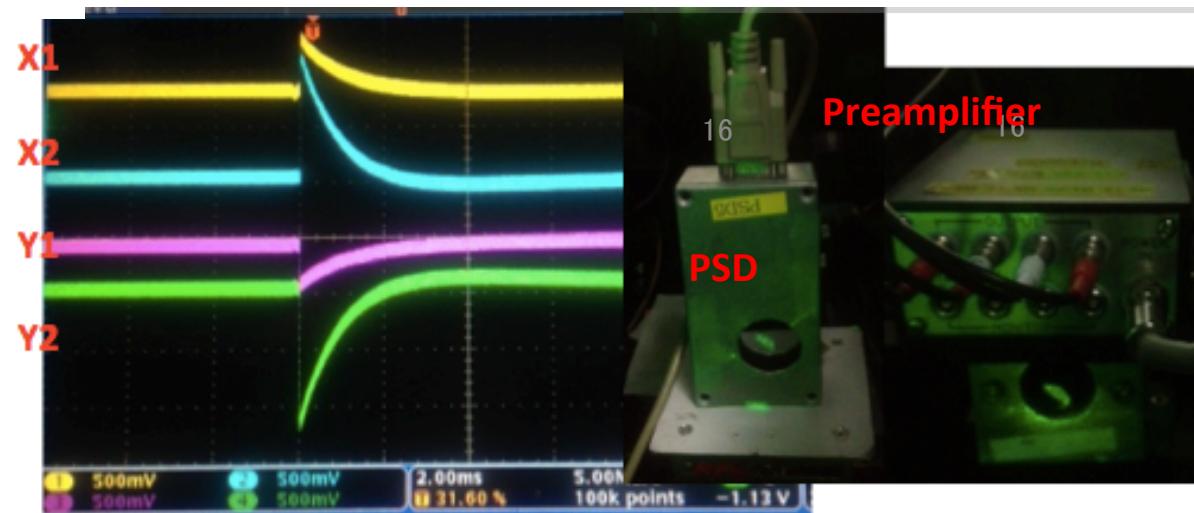
Hardware (re)commissioning PSDs, phase monitor, profile monitors, DAQ modules, ect....

Tests of PSDs (+ preamps, readout circuit)



CCD camera
as
profile monitor

Signal output from PSD electrodes



SUMMARY

IPBSM (“Shintake Monitor”) installed at ATF2 IP

- use **laser interference fringes**
→ **only device capable of measuring $\sigma_y^* < 100 \text{ nm}$**
- Crucial for beam tuning → realization of future linear colliders

< Status >

- ❖ **Stable measurements of $\sigma_y^* \sim 160 \text{ nm}$ (30° mode)**
- ❖ dedicated systematic error study (2 – 8 °mode)

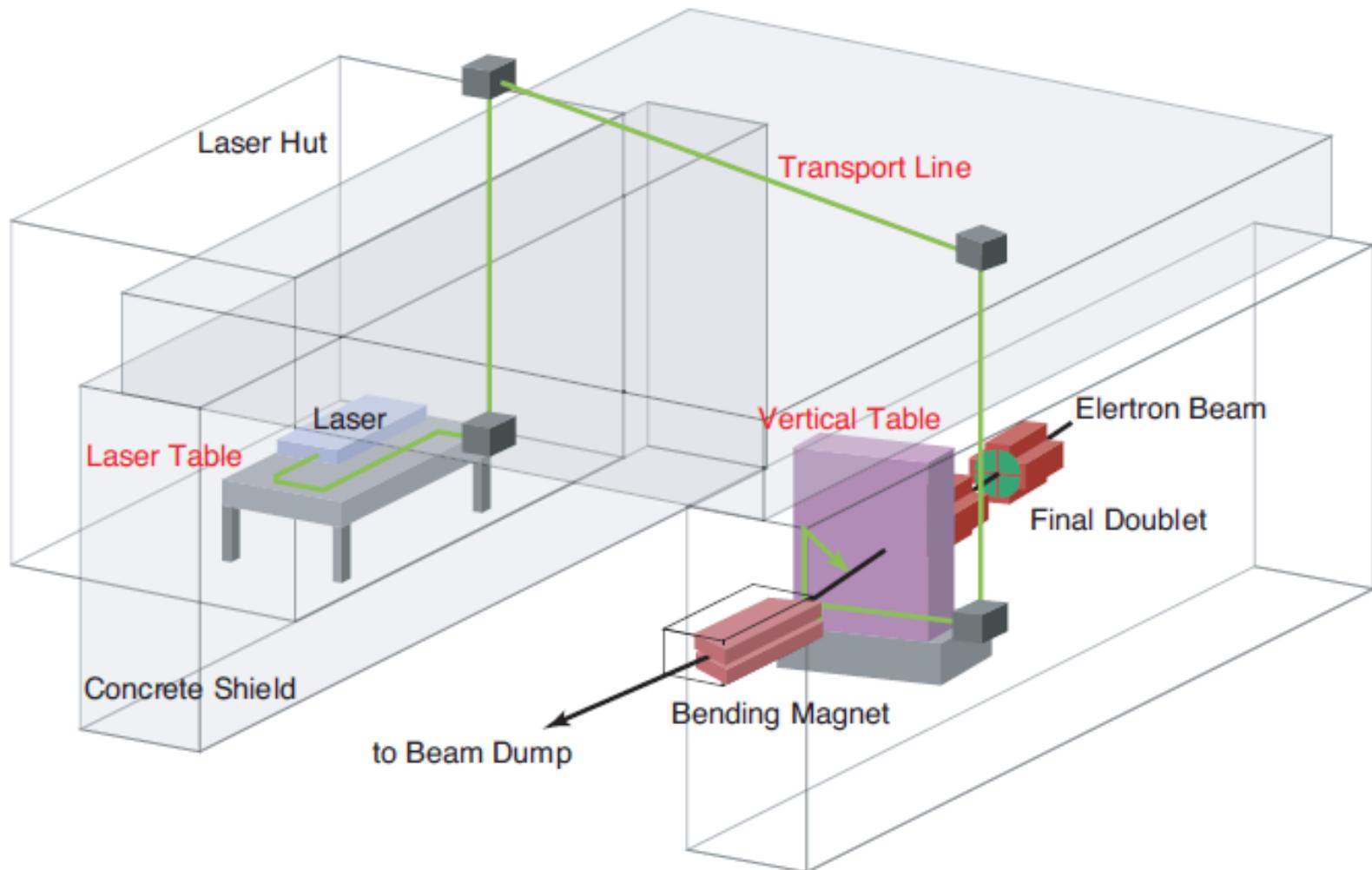
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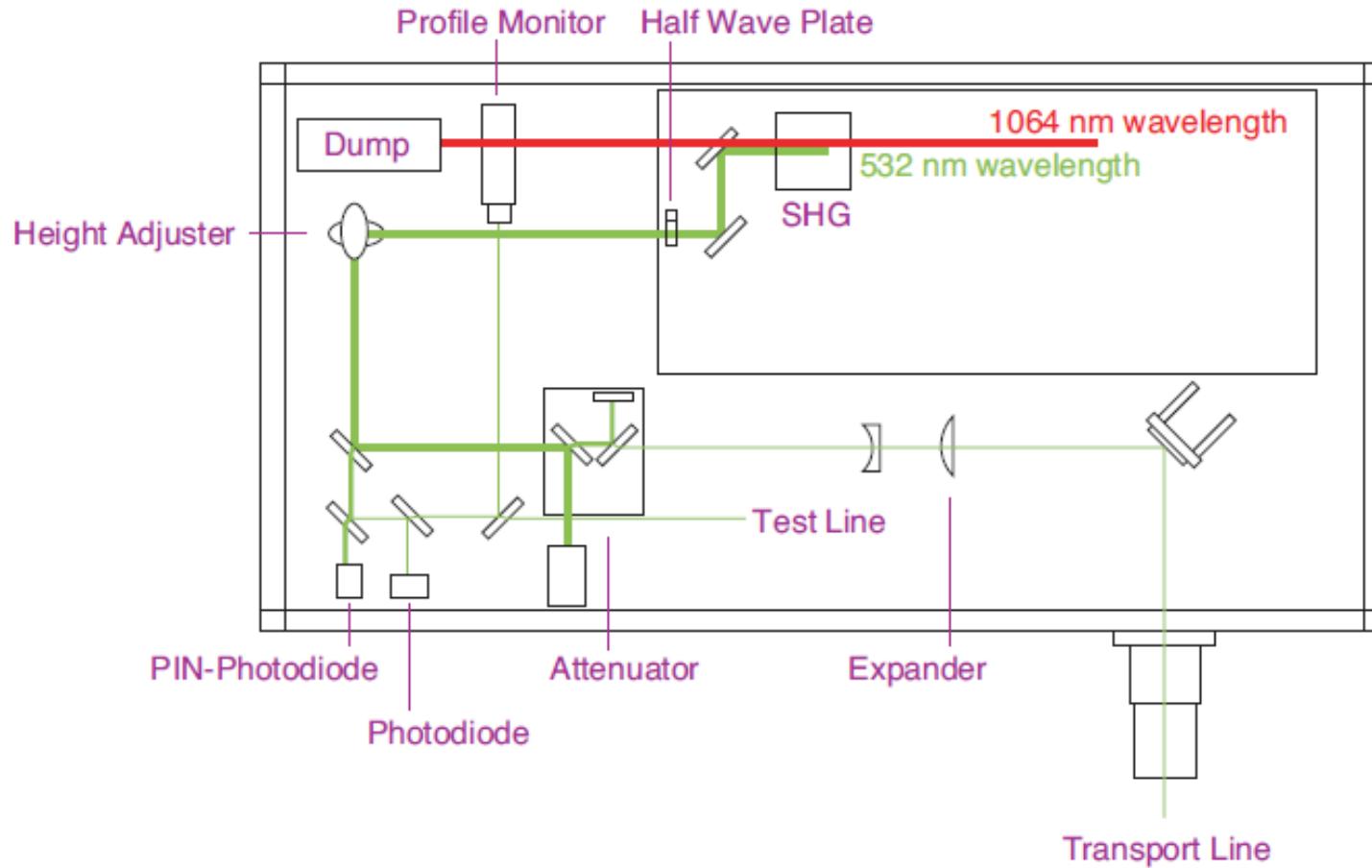
- suppress jitters & bias factors
- stabilize laser system
- **reliability & reproducibility in laser optics alignment**

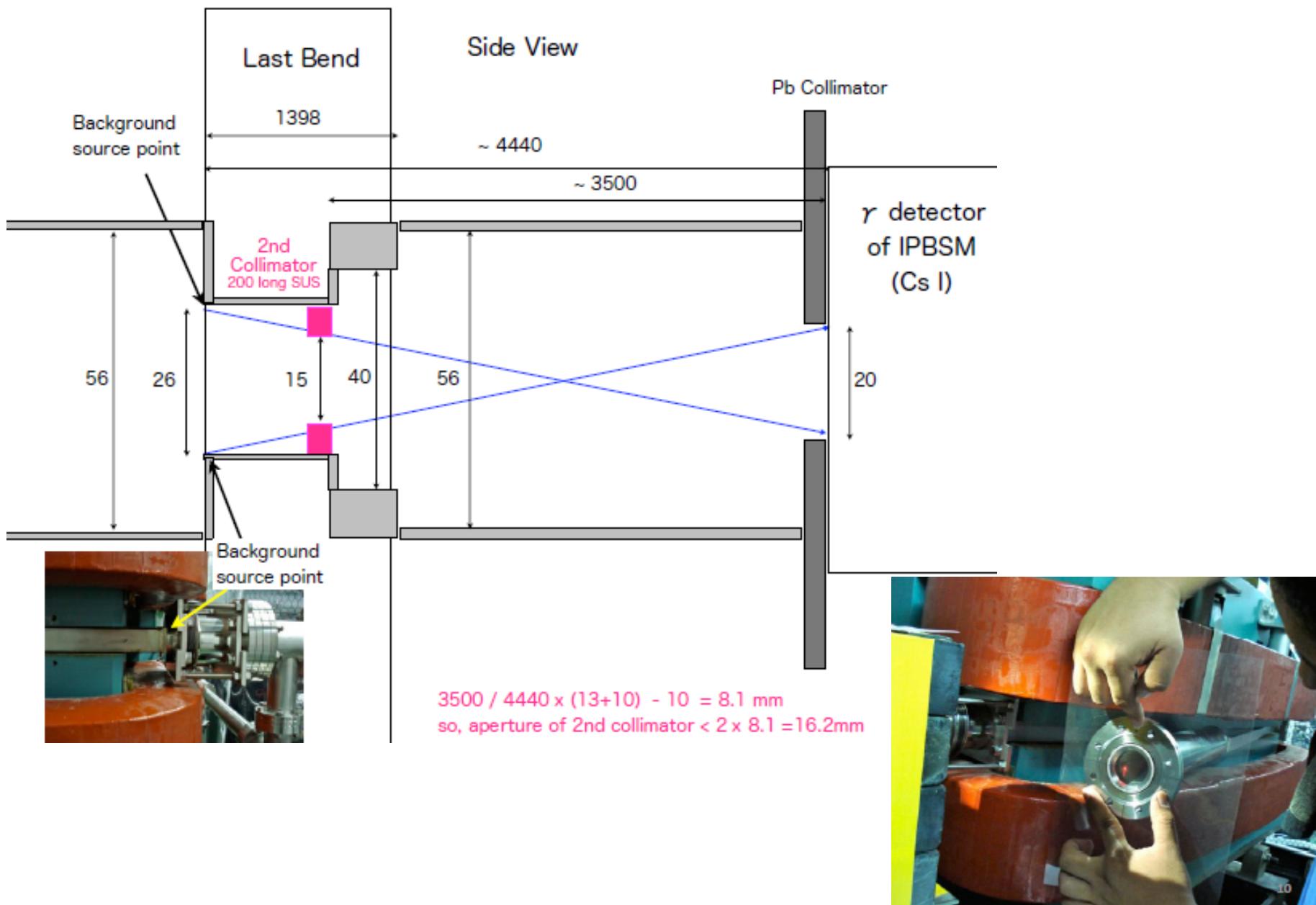
< Goals for 2012 autumn beam run>

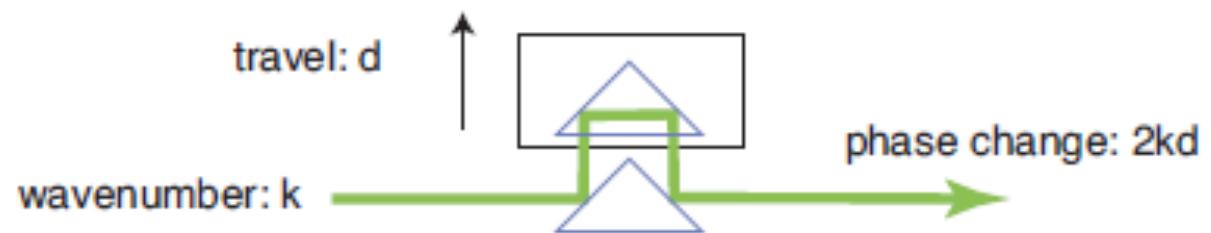
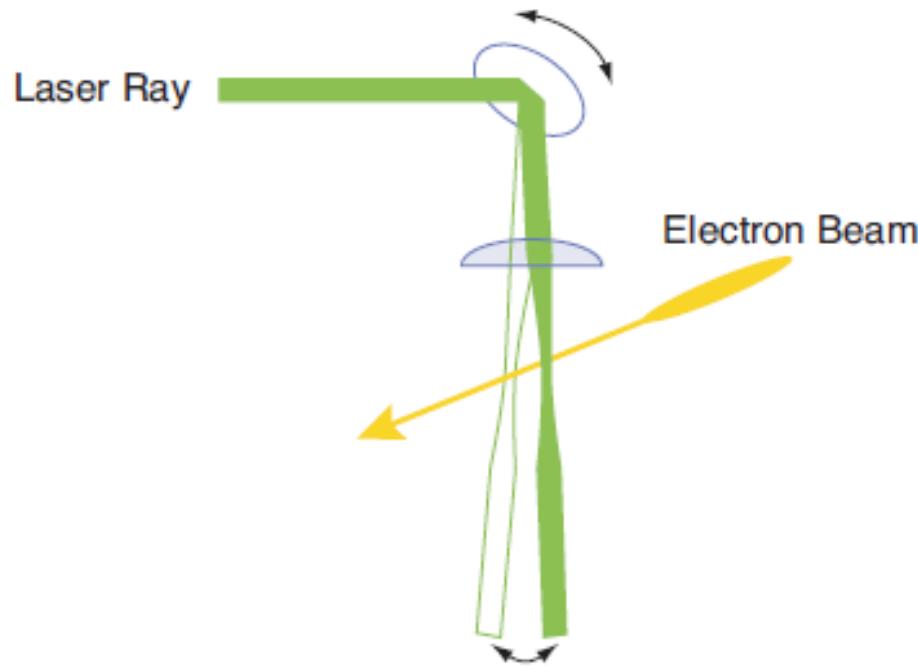
- ◆ full commissioning of 174 ° mode
- ◆ stable measurement of $\sigma_y^* < 100 \text{ nm}$
→ achieve focusing down to $\sigma_y^* \sim 37 \text{ nm}$

BACKUP

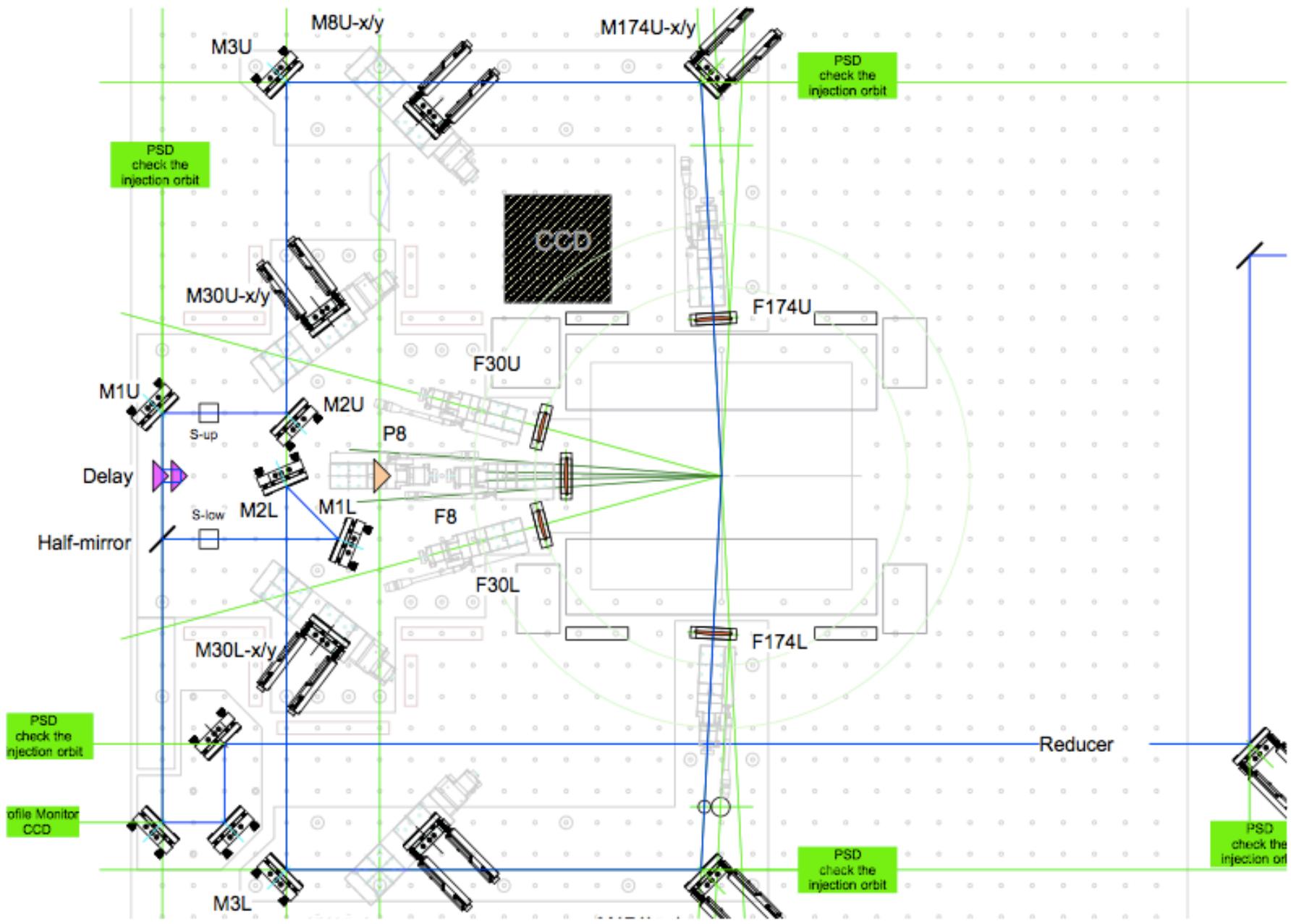








New 174 mode



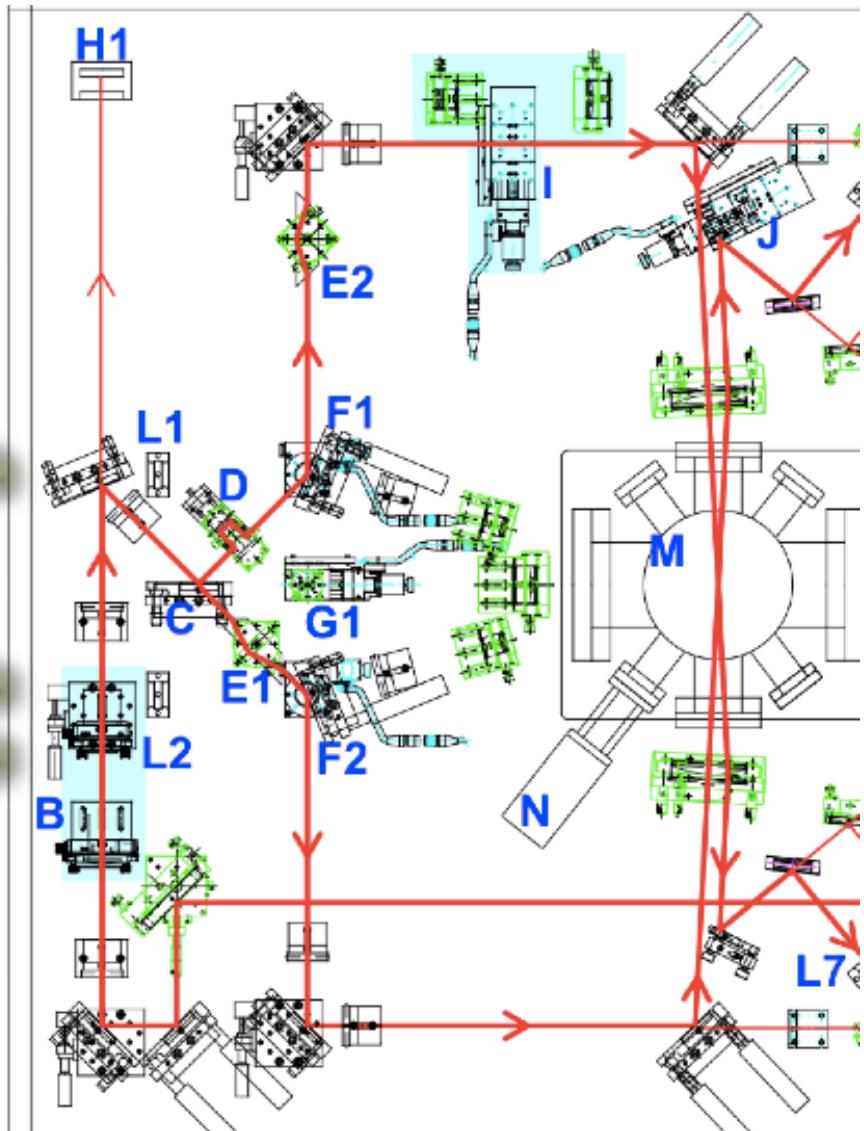
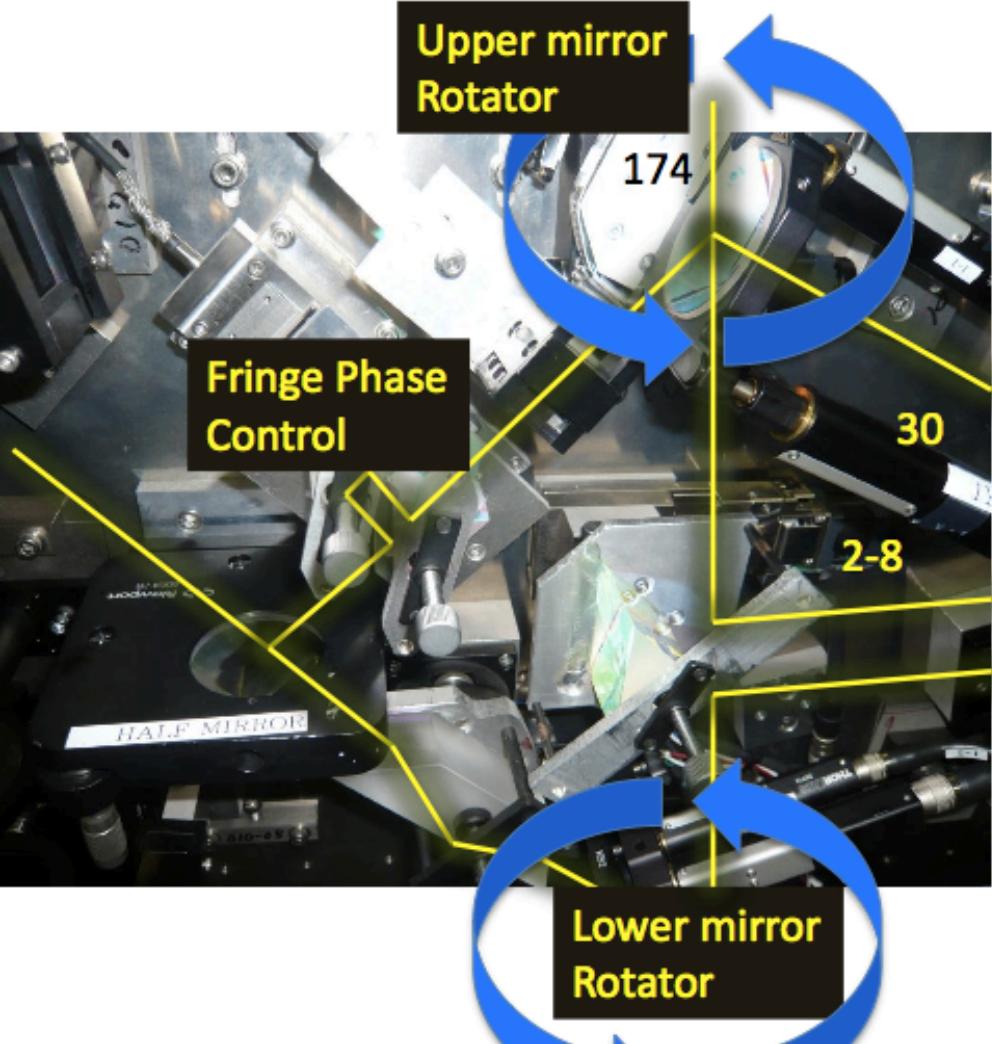


Table 3: Upper limits of each M reduction factor predicted for measuring the design $\sigma_y^* = 37$ nm at ATF2. Assumed here are nominal laser and ATF2 beam parameters, as well as implementation of specific correction functions for the sensitive 174 deg mode used in this case[6].

Modulation reduction factor	37 nm at 174 deg
Total power imbalance	> 99.8 %
Relative position jitter	> 98.0 %
Fringe tilt	> 97.2% (tilt < 1 mrad)
Alignment (t, z)	(> 99.6%, > 99.1 %)
Spatial coherence	> 99.9%
Spherical wavefronts	> 99.7%
Beam size growth within fringe	> 99.7%

Table 4: Upper limits of dominant M reduction factors for measuring $\sigma_y^* \sim 500$ nm at 4 deg mode, estimated using data from June, 2012

Modulation reduction factor	O(500) nm at 4 deg
Profile imbalance (t, z)	(> 94%, > 89 %)
Relative position jitter	> 95 %
fringe tilt (t, z)	> 95% (tilt < 20 mrad)
Alignment (t, z)	(> 95%, > 99 %)
Polarization	> 98%

laser path misalignment

1 . Laser profile imbalance

misalignment of final lens focal point
divergence angle affected by reducer setup

In past:

replaced damaged optical components
optimized lens / reducer setup, alignment methods

2. Laser position offset from IP (beam center)

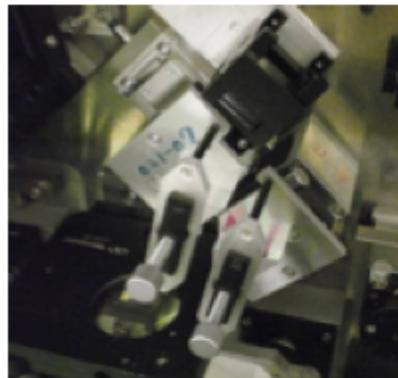
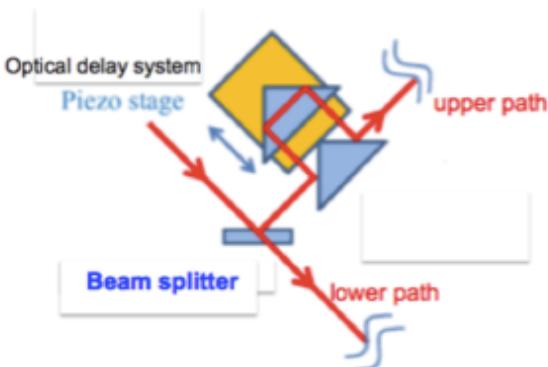
→ not a concern,
mirror actuators finely adjust
to 1/10 of σ_{laser}

long. : Cz- pos > 99.5 %
transv : Ct-pos ~ 100%

Polarization related errors

→ imbalance in intensity/ profile

→ half mirror R = 50% only for pure S state
elliptical components (P contamination)



adjust to S state
by rotating $\lambda/2$ wave plate

• measured in past :
half mirror properties,
eccentricity Es : Ep = 1: 0.13

→ $C_{\text{pol}} = 97.8 \pm 12.8 \cdot \tan\theta \pm 0.1\%$
(2-8, 30 deg)

$C_{\text{pol}} = 97.2 \pm 1.3 \cdot \tan\theta \pm 0.1\%$
(174 deg)

for now assume $C_{\text{pol}} \sim 98\%$

Figure 4.7: [Left] The optical delay system for controlling fringe phase. [right] The piezoelectric stage

顕著な系統誤差

(2012連続ランより)

夏の光学系アップグレードで系統誤差を改善

Profile Imbalance

- ✓ Compton peak power の違い: $C_{\text{pow}} \sim 98\%$
- ✓ IP spot size σ_{laser} の違い: $C_{\text{pro}} \sim 90 - 95\%$

◆一部は光学素子由来のロス
(反射・透過率、光路長差ect...)
total $P_l = 0.88 \leftrightarrow C = 99.8\%$

◆lensのalignment精度
(→ 焦点位置のばらつき)

実laserwire
scan

$$M' = CM = \frac{2\sqrt{P_l}}{1+P_l} M$$

$$P_l \equiv P_U / P_D$$

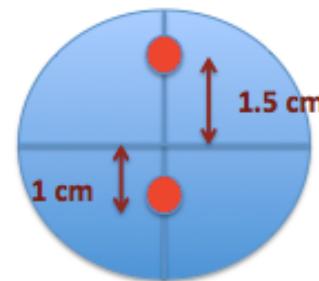
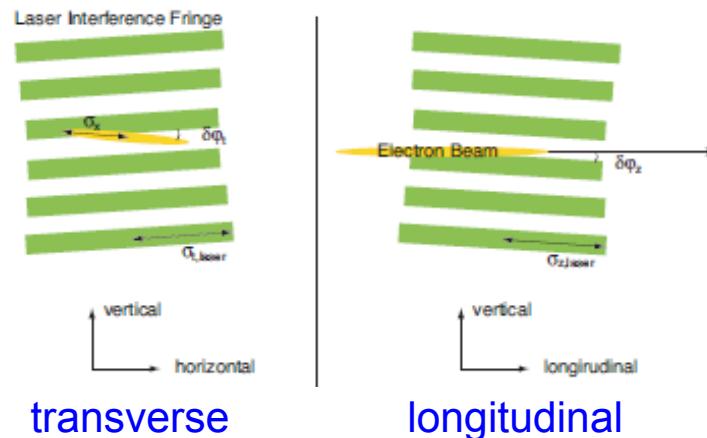
上パス

下パス

上図) 2倍の信号量の差

Fringe Tilt

干渉縞がbeam軸に垂直でない場合

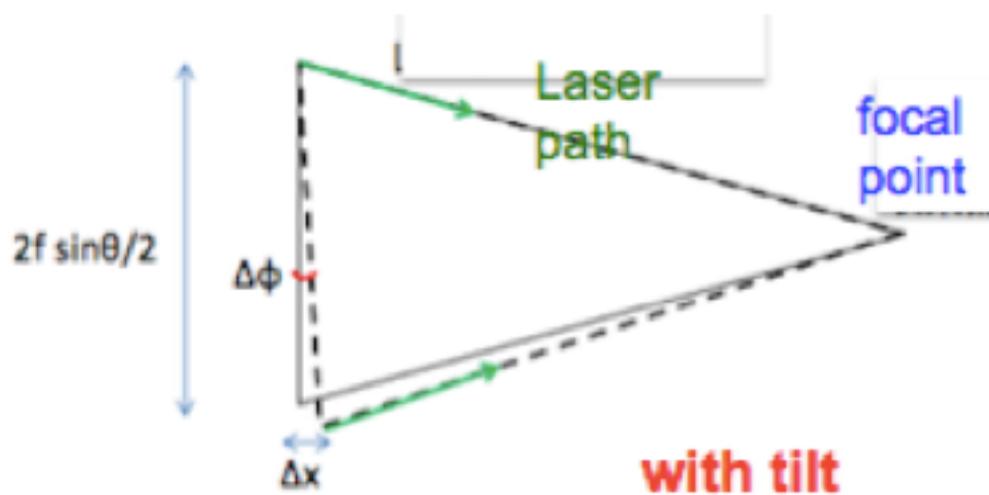
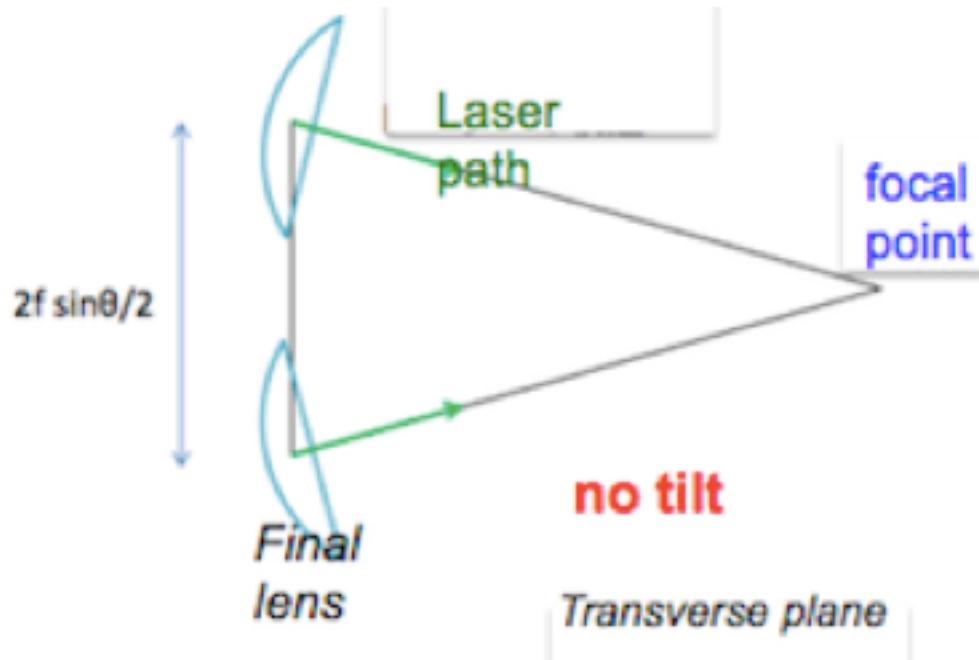


見積もり方:
収束レンズ中心からの
相対的オフセット $\Delta t, z$

光路精度 $\Delta < 3 \text{ mm}$

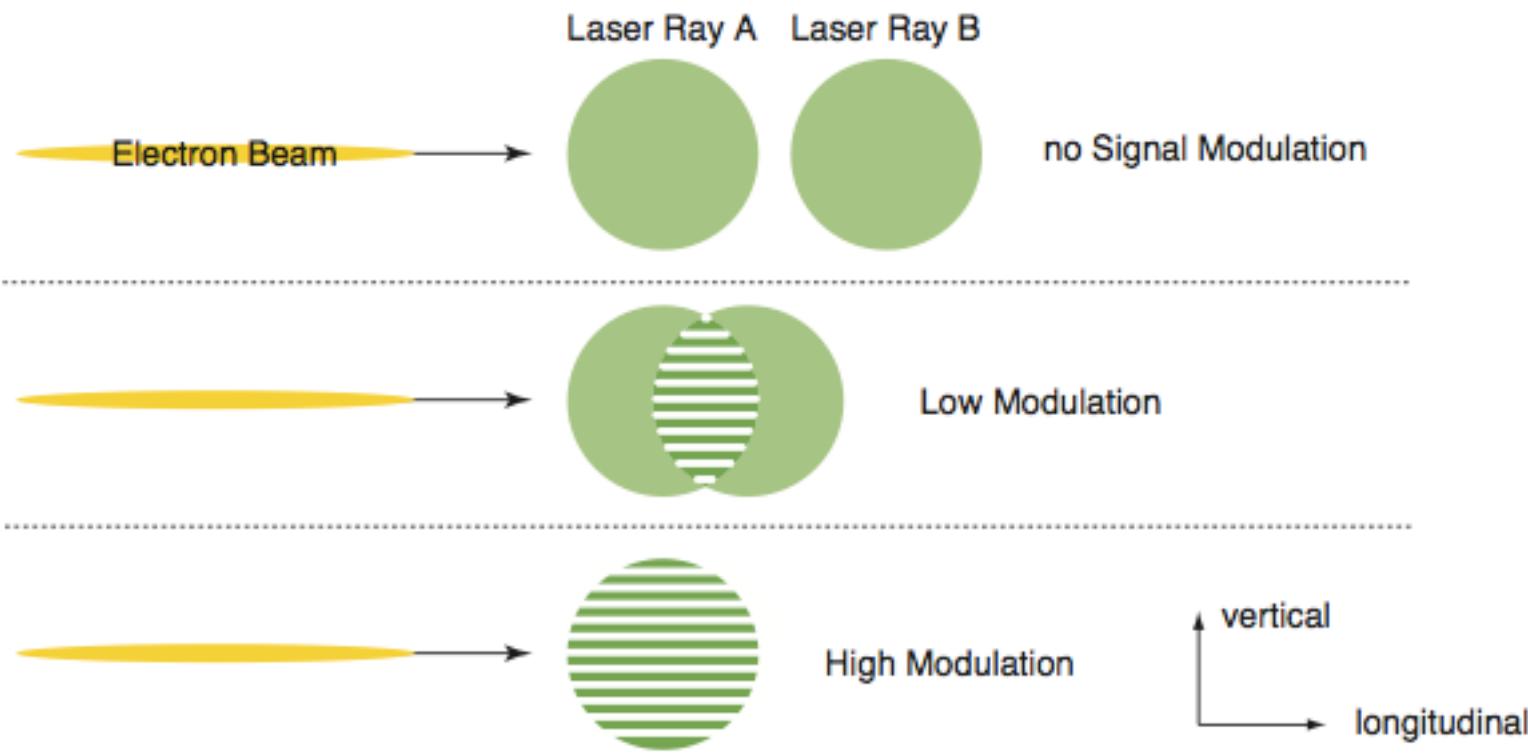
→ 傾き: $\delta\phi_t < 10 \text{ mrad}$
 $\delta\phi_z < 5 \text{ mrad}$

$C_{\text{t-tilt}} > 95.3\%$
 $C_{\text{z-tilt}} > 99.8\%$

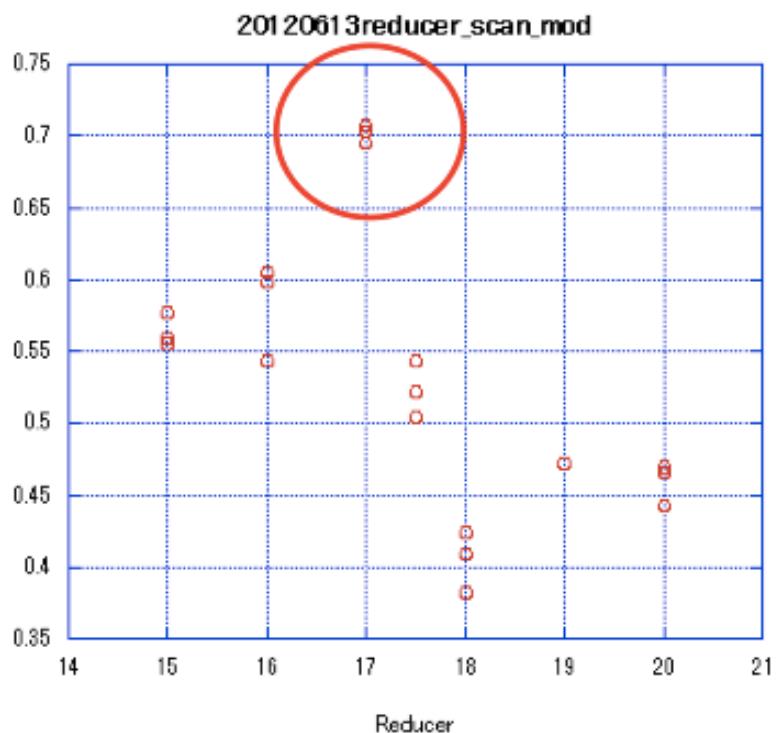


$$\tan \Delta\phi = \Delta x / 2f \sin\theta/2$$

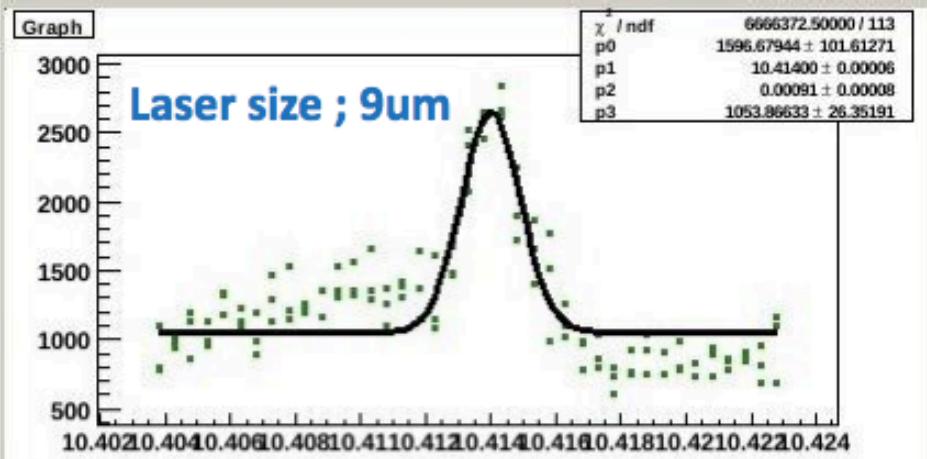
Transverse plane



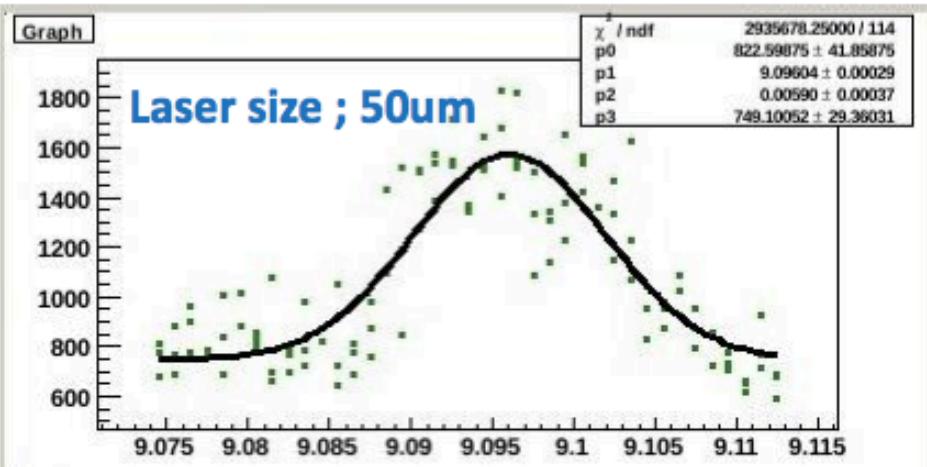
○ mod



Very narrow optimum setting



Beam profile of lower path



Current status of laser system

Stat errors

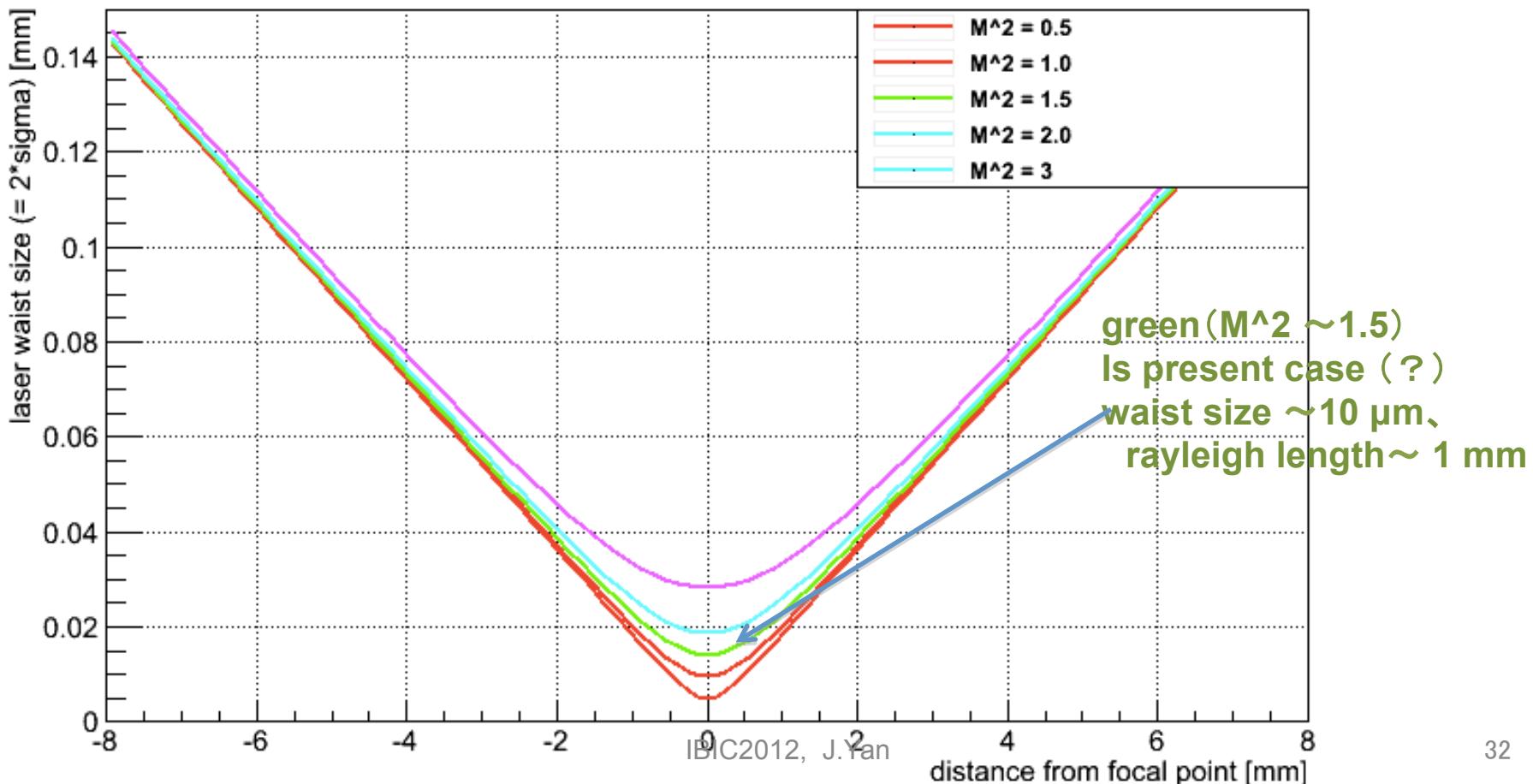
relative timing	Stabilized by timing scans TDC, TD2 modules	Laser timing	1 - 3 %
Intensity	<ul style="list-style-type: none"> • Stability ~ 1% • optics damaged by high intensity laser in March • Safe at ~ 40% power for now 	Laser intensity	1.5%
Oscillation	<p>currently stable</p> <ul style="list-style-type: none"> • exchanged flash lamps and seeder • cavity mirror tuning 	Beam intensity jitters	ICT monitor resolution: 2-5% (Measured energy is normalized by ICT)
profile	<p>Triangular (non-Gaussian) profile at IP dark spots</p> <p>→ Improved by rear mirror tuning</p>	Laser pointing stability	10 ~ 15%
Major upgrades in laser optics	<ul style="list-style-type: none"> • Beamlok • new laser table box • additional mirror for precise injection onto vertical table • changed reducer and expander lens (AR coating , magnification) 	Beam position jitters	unknown

M^2 : 0.5 – 3.0

near field to few times of rayleigh length

- Assume injected size of $\omega = 4.5$ mm,
- fix focal point to 5.6 mm (lens mover position)

beam focusing dependence on M^2



4 consistent measurements at 4 deg mode :

including long range fine scan (60 rad, Nav = 10)

M = 0.887 ± 0.005 (stat only) **$\sigma_y = 589 \pm 13 \text{ nm}$**

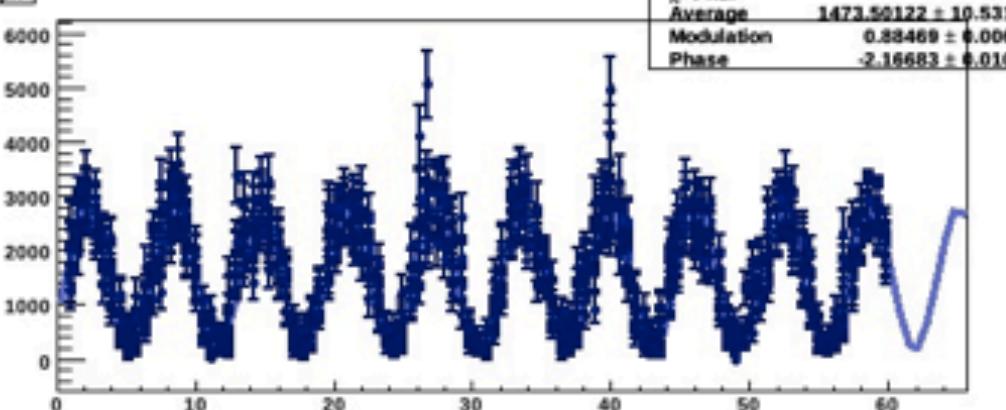
init. phase: **-2.162 ± 0.009 rad**

phase drift ~ 18 mrad (~ 0.8 % only)

Rotation Control | TD2 FineDelay | LW28 | LW30 | LW174 | Fringe28 | Fringe30 | Fringe174 | Zscan28 | Zscan30 | Zscan174 | 2-8 |

Fringe Scan 2-8 degrees

Graph



Phase Scan Range

Min: 1.00 Max: 60.00 Step: 0.60 Nread: 10

Origin Phase Position: 1.2609

Current Phase Position: 1.23711

Intensity Cut [e9]: 2.000 < I < 10.000

Fit Mode: layer 1-4 3.637

Start

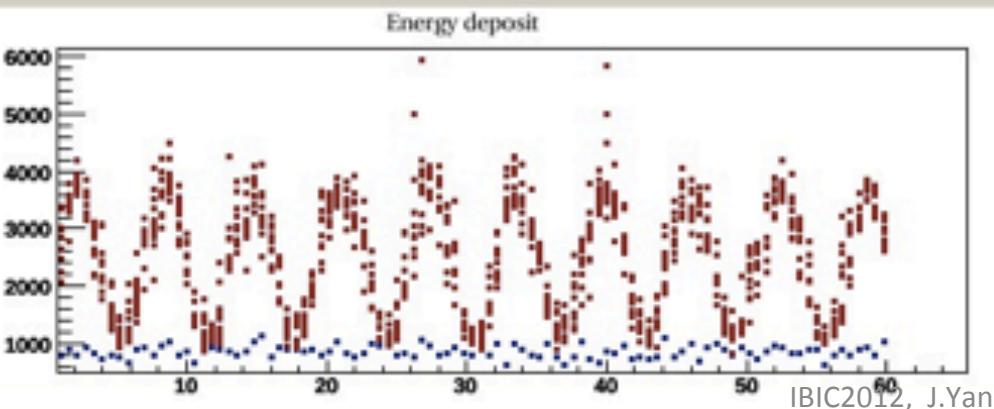
Stop

Collision Angle: 4.00907

Filename: /atf/data/ipbsm/interfere/meas120614_231021.c

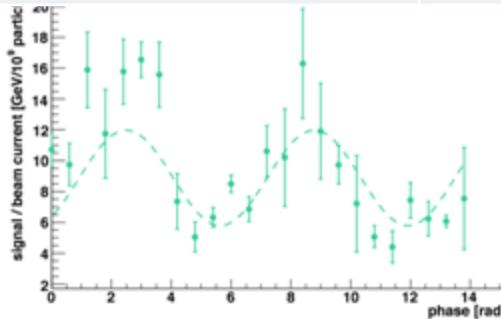
FileSelect

Recalculation

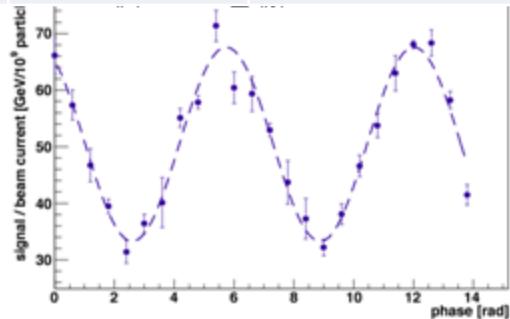


Modulation	0.885	+/-	0.006
Beam Size	593.1	+/-	15.5 nm
Average	1473.501	+/-	10.531
Phase	-2.167	+/-	0.010

optics for recent run	S/N	BG [GeV]	Sig. jitter
10x βy^* (ex: 30 deg)	4	5	15 – 25%
3 x βy^* (ex: 2- 8 deg)	1	15	
1 x βy^* (ex: 174 deg)	0.5	20	BG のふらつき ~10 – 15 %

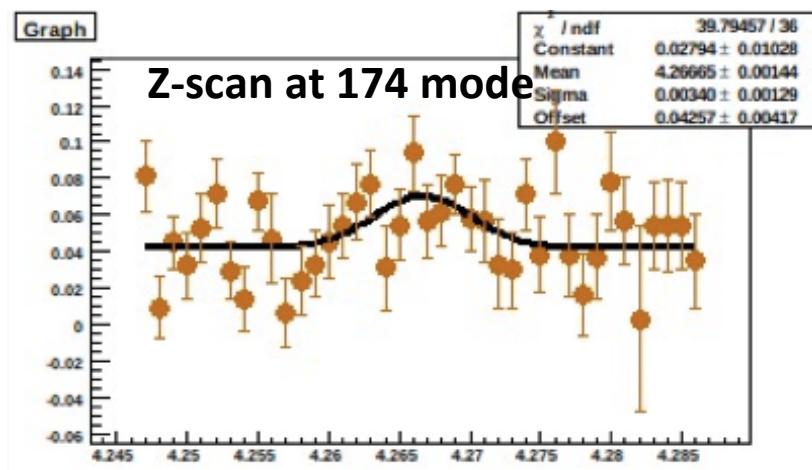


シグナルジッター: 30%



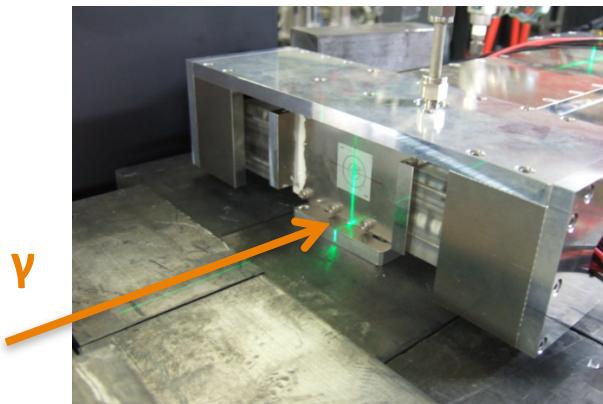
シグナルジッター < 10%

ハードウェアアップグレード

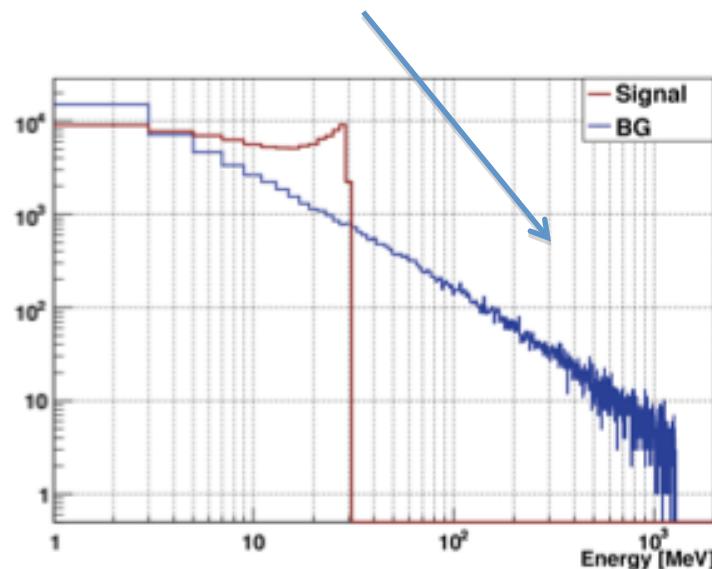


ガンマ線検出器

カロリーメータ型CsI(Tl)シンチレータ



ATF2 で signal と BG エネルギースペクトル
が大きく違うことを活用

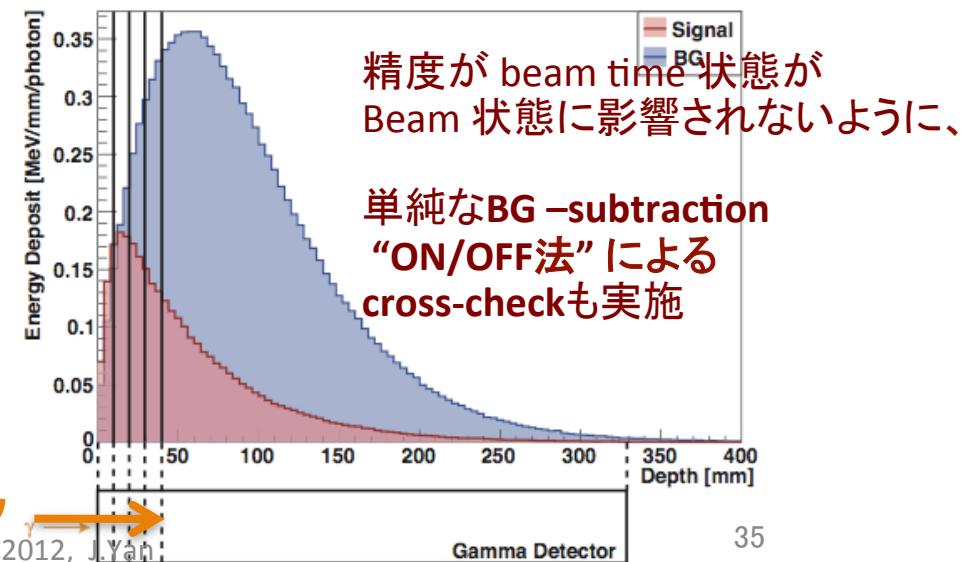


多層構造

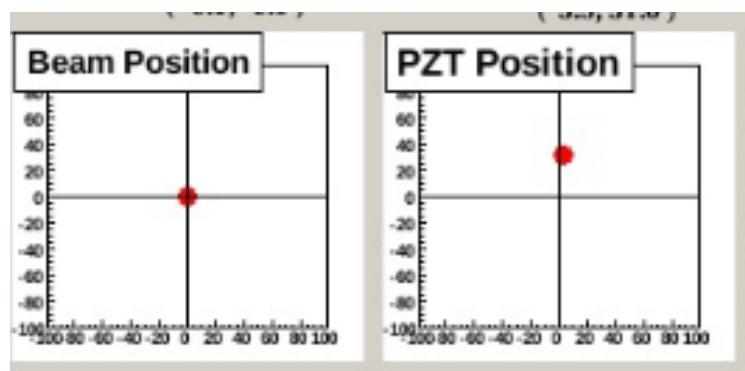
前4層 (10 mm x 4) + 後ろの "bulk" (290 mm)

高いシグナル・BG分離能

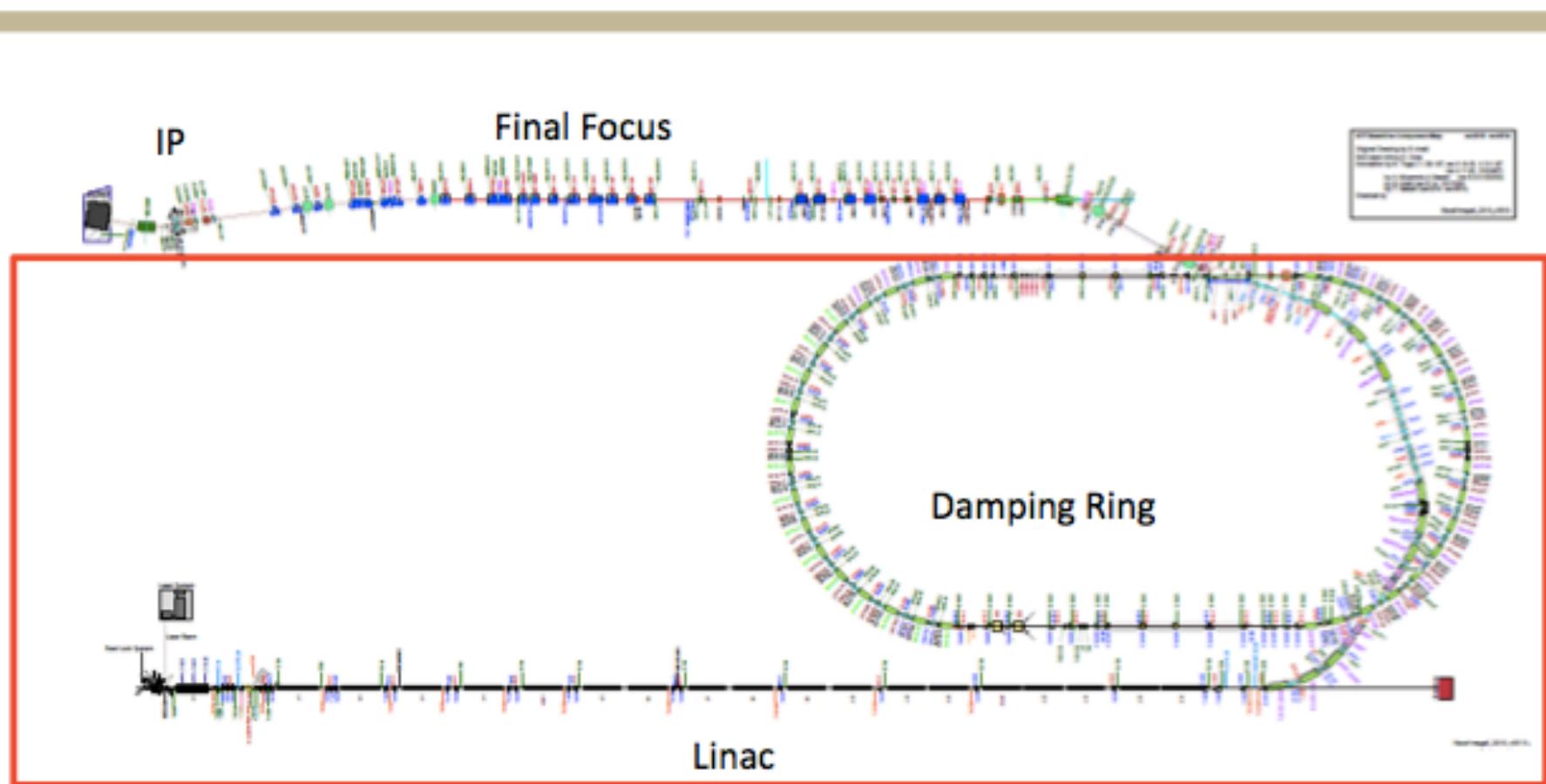
各層でのシャワー発展を測定
→ 参照シャワーで fitting



BeamLok Specifications	Standard Pro Series	With BeamLok/D-Lok
Beam Pointing Stability ¹²	<±50 µrad	<±25 µrad
Beam Divergence ¹³	<0.5 mrad	<2 x initial level
Lamp Lifetimes ¹⁴	30 million pulses	40 million pulses
Linewidth		
Standard		<1.0 cm ⁻¹
Injection Seeded ¹⁵		<0.003 cm ⁻¹
Timing Jitter ¹⁶		<0.5 ns



ATF



Linac: ピームエネルギー 1.3 GeV

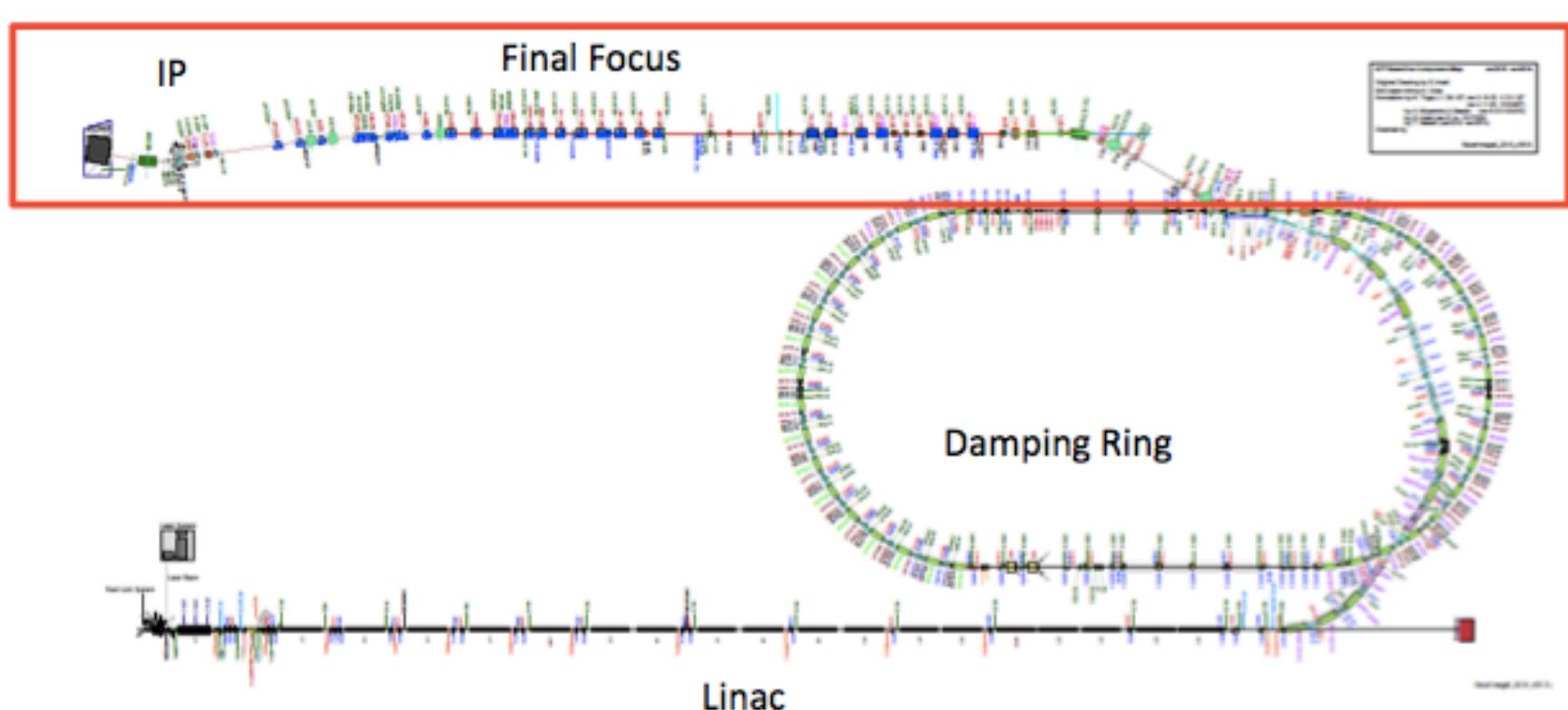
Damping Ring: 鉛直エミッタンス $11 \text{ pm} \cdot \text{rad}$



規格化鉛直エミッタンス $30 \text{ nm} \cdot \text{rad}$

ILCでの規格化エミッタンス $35 \text{ nm} \cdot \text{rad}$

ATF2



Final Focus: 局所色収差補正に基づいた設計

- 37 nmの鉛直ビームサイズ → 新竹モニタで測定
- nmレベルのビーム安定化 100 nm以下のビームサイズ測定に実績

FFTB vs ATF2



Table 2: Typical e- beam and IPBSM parameters: ATF2 vs FFTB[2, 4]

	FFTB	ATF2
Beam energy	46.6 GeV	1.28 GeV
1 photon energy	8.6 GeV	15 MeV
rep. rate	30 Hz	1.56 Hz (3 Hz)
e- / bunch	1×10^{10}	1×10^{10}
Bunch length	3 ps	16 ps
(σ_x^*, σ_y^*) at IP	(900, 60) nm	(2200, 37) nm
Laser wavelength	1064 nm	532 nm (SHG)
Range for σ_y^*	40-720 nm	20 nm-6μm

